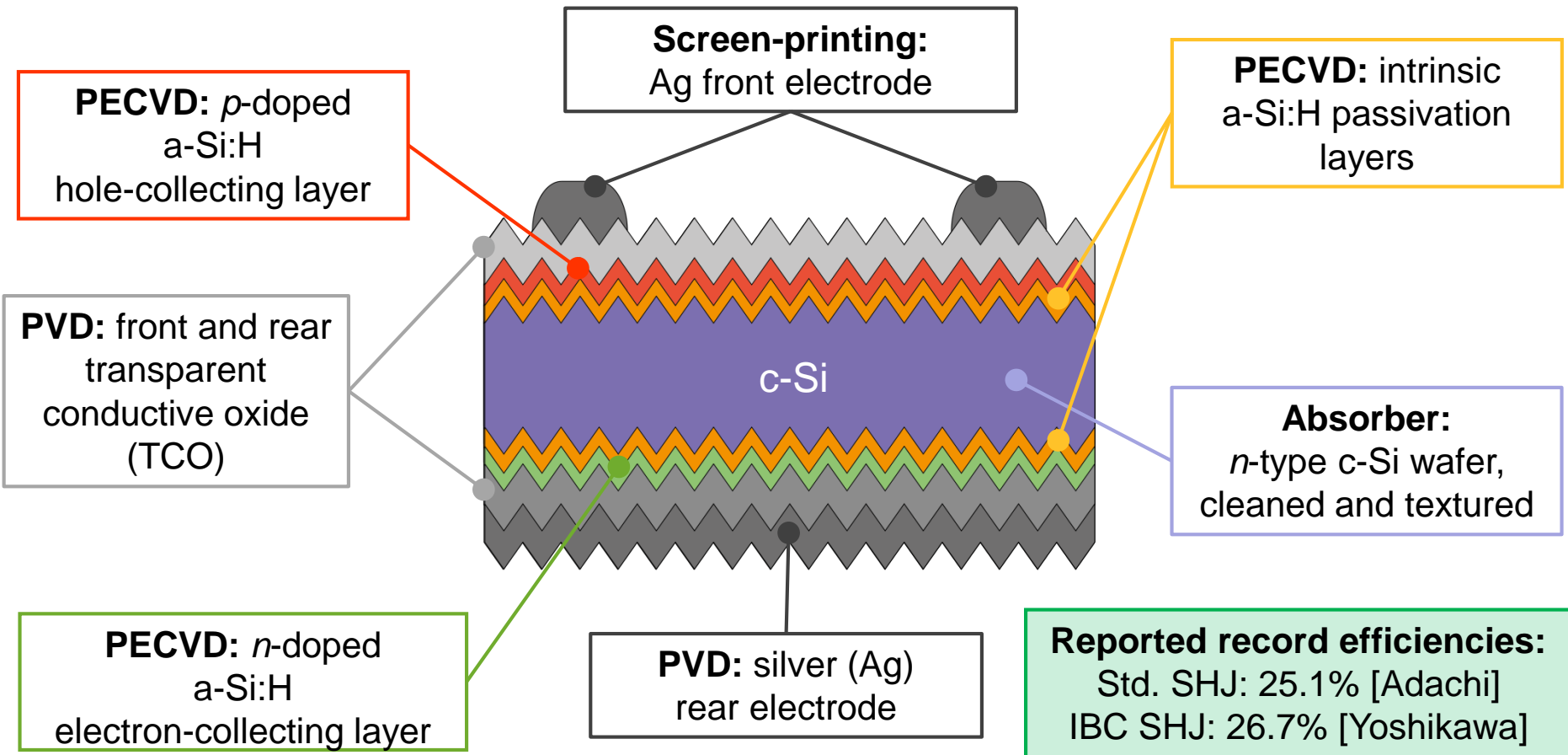


**WINDOW LAYERS FOR  
SILICON HETEROJUNCTION SOLAR CELLS:**  
*Properties and Impact on Device Performance*

Johannes P. Seif

# Silicon Heterojunction Solar Cells



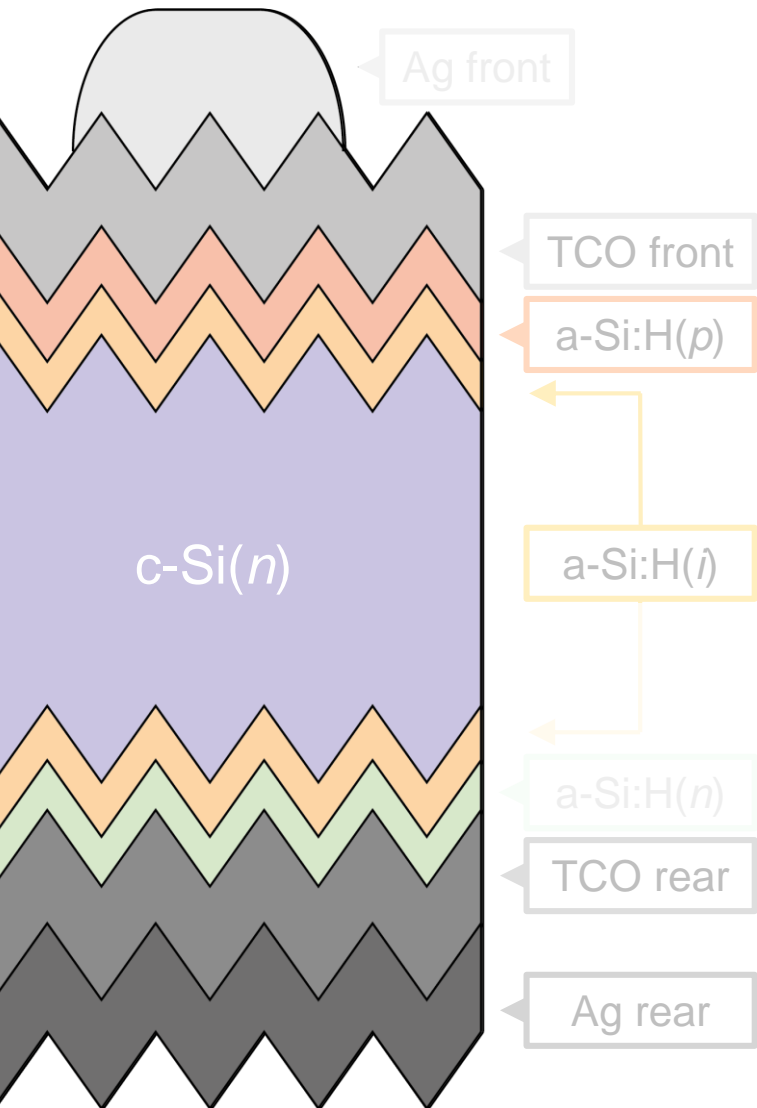
Physical Vapor Deposition / Sputtering (PVD)

Plasma Enhanced Chemical Vapor Deposition (PECVD)

*D. Adachi et al., APL, 2015, 107, 233506.*

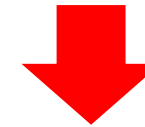
*K. Yoshikawa, Nature Energy, 2017, 2(5), 17032.*

# Challenges: *optical losses*



**Parasitic absorption in the front layers:** generation of charge carriers that recombine before being collected.

**-2.1 mA/cm<sup>2</sup>**



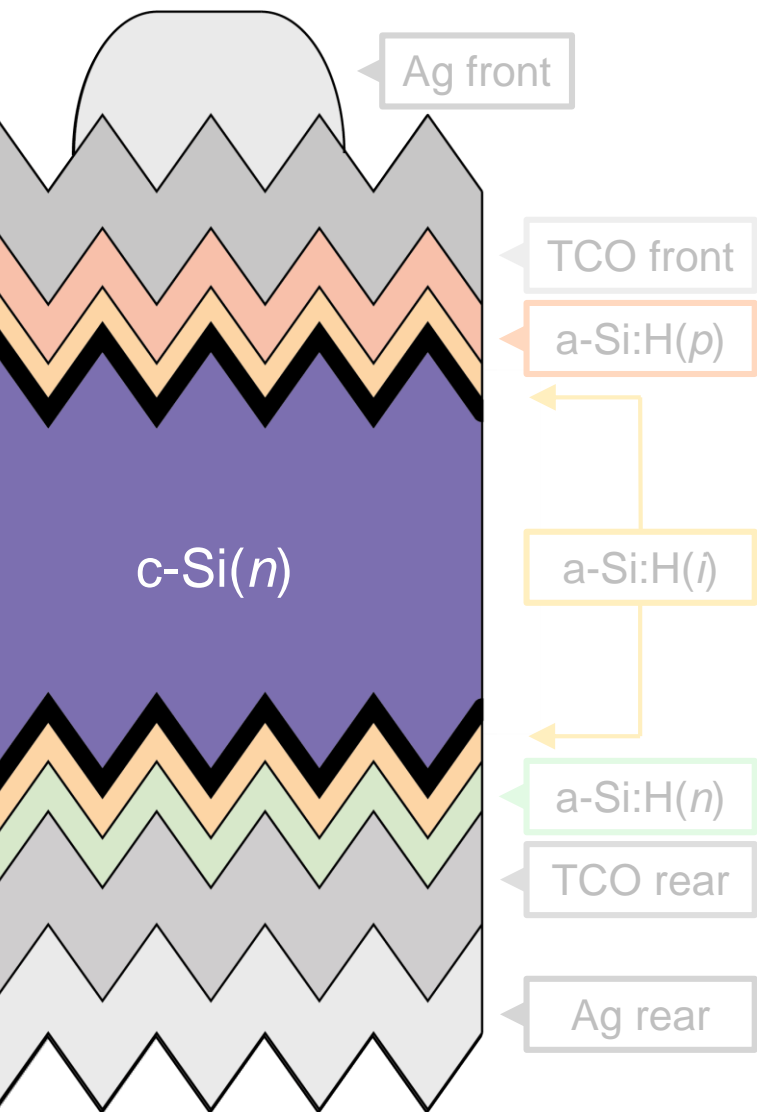
**Lower** current output of the device, *i.e.* reduced **short-circuit current density ( $J_{sc}$ )**



**-0.5 mA/cm<sup>2</sup>**

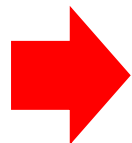
**Free-carrier absorption** in the highly doped TCO layer & **plasmonic losses** in the metal rear reflector.

# Challenges: *electrical losses*



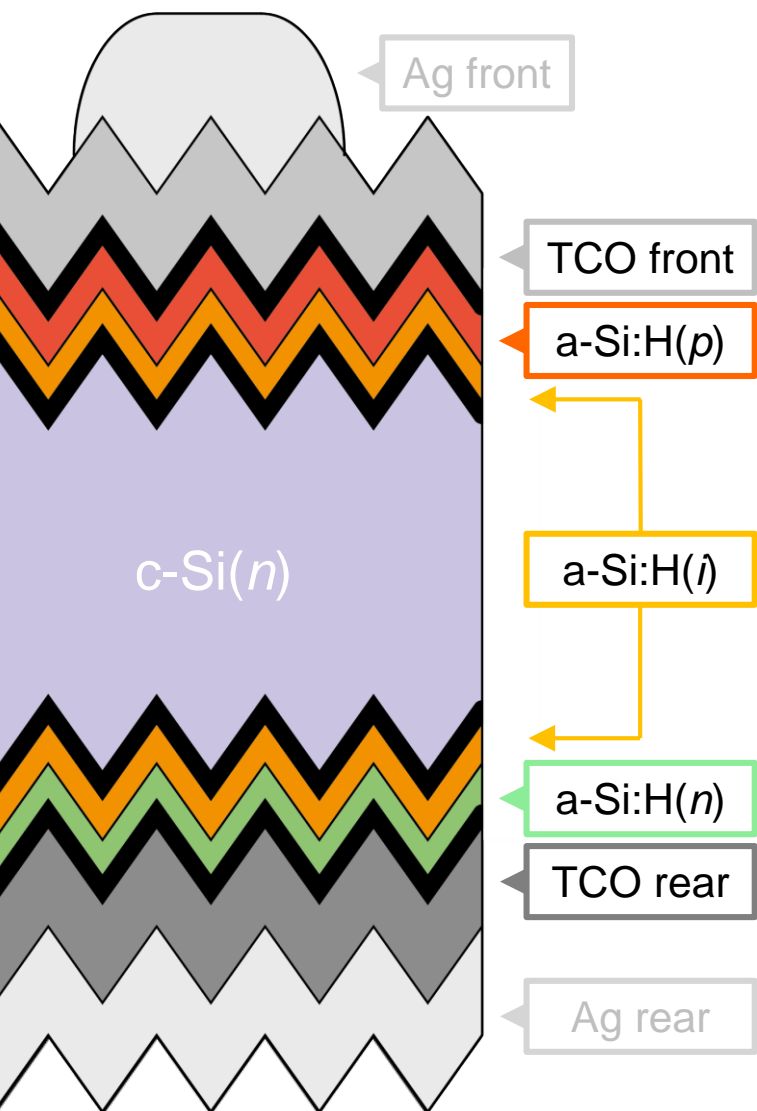
## Recombination

- Radiative
- Auger
- Via defect states in the bulk or at the surface



**Lowers** the maximal attainable voltage, *i.e.* the open-circuit voltage ( $V_{oc}$ ) and **limits** the voltage at the maximum power point (fill factor,  $FF$ )

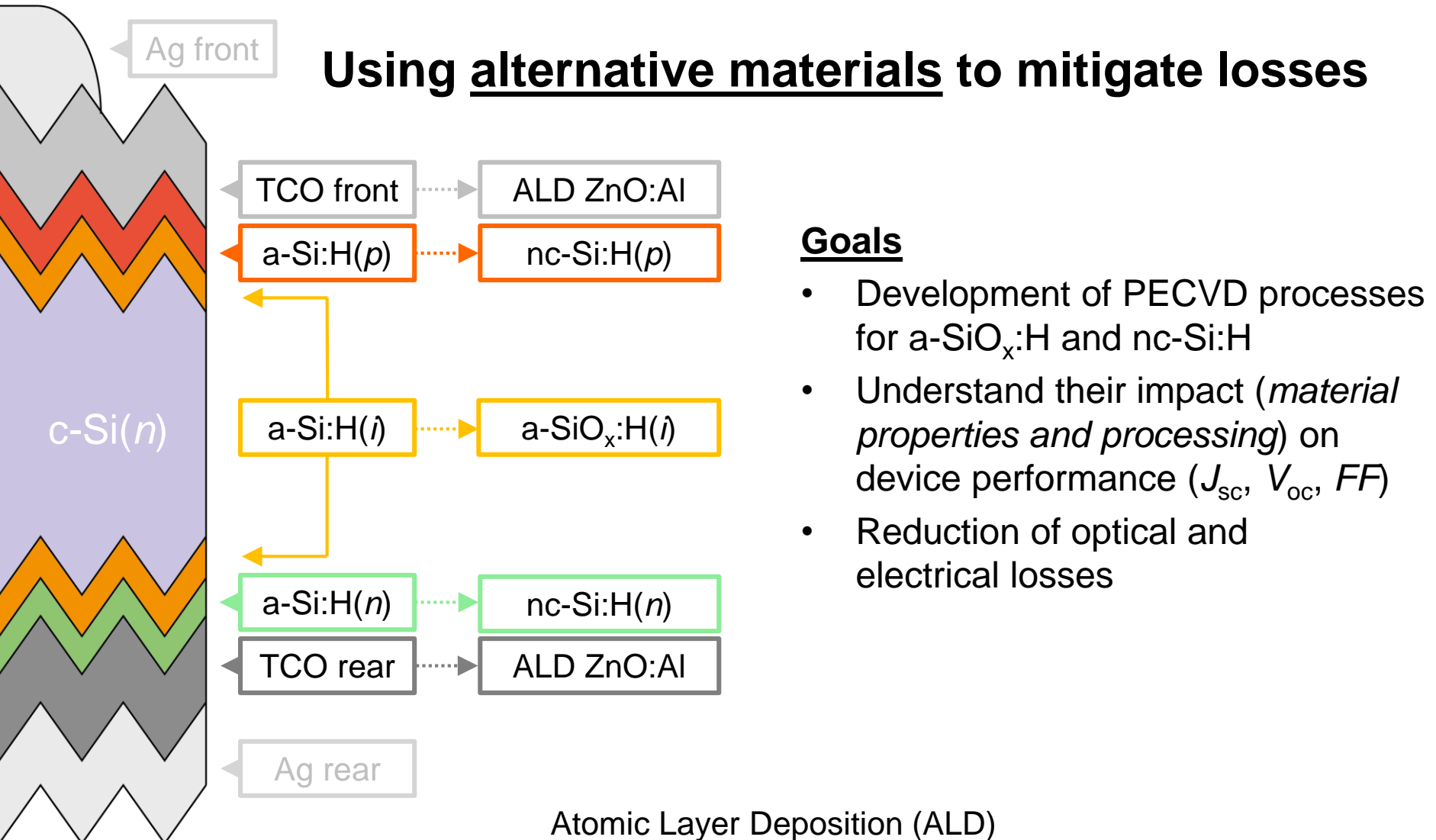
# Challenges: *electrical losses*



**The Transparent Conductive Oxide (TCO)** can have an influence on the a-Si:H layers (Schottky barriers) and the a-Si:H/c-Si interface (increased recombination).

**Lowers** the maximal attainable voltage, *i.e.* the **open-circuit voltage** ( $V_{oc}$ ) and **limits** the voltage at the **maximum power point** (fill factor,  $FF$ )

# Motivation



# Outline

**Temperature coefficients**  
Temperature impact  
on lifetime and cell performance

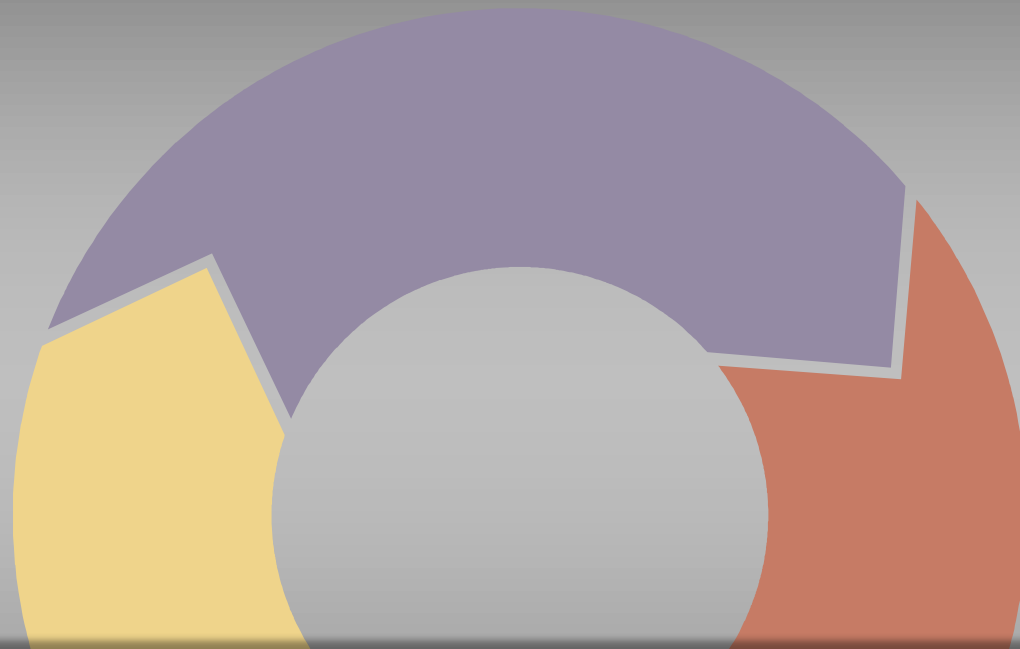
**Wide-bandgap materials**  
a-SiO<sub>x</sub>:H for passivation  
band offsets and transport barriers

**Alternative transparent electrodes**  
atomic-layer-deposited ZnO:Al  
as protective layer vs. sputter-damage

**Organic overlayers**  
spin-coated PVK for work function  
engineering

**Nanocrystalline layers**  
Deposition strategies &  
device performance



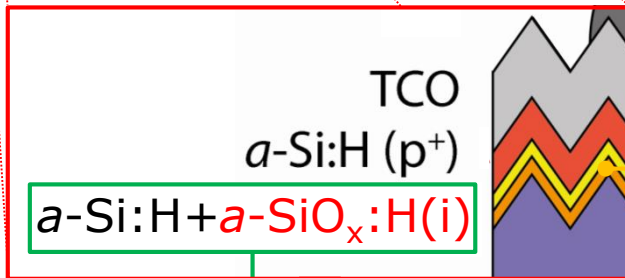
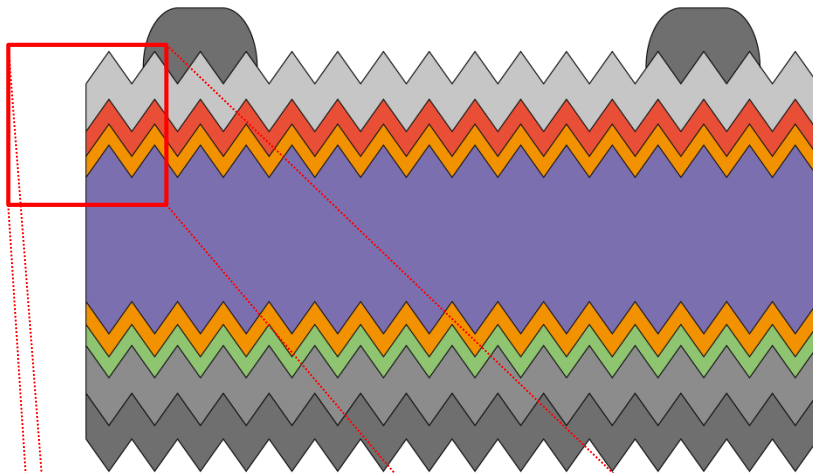


## Wide-bandgap materials:

*a-SiO<sub>x</sub>:H – optical gain versus transport*



# Motivation



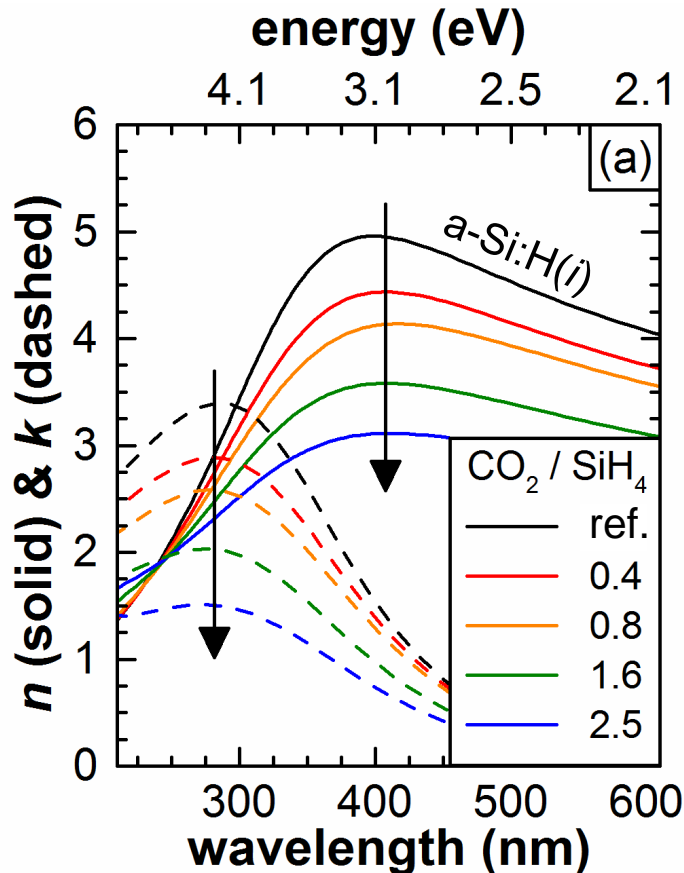
More transparent  
front side  
 $\rightarrow J_{sc}$  gain

Variation of...  
 $i$ -layer thickness,  
 $[\text{CO}_2]/[\text{SiH}_4]$  and  
device structure.

In this section:  $i$ -layer

**NOTE:** Using  $a\text{-SiO}_x\text{:H}$  only  
 $\rightarrow$  sub-optimal passivation

# a-SiO<sub>x</sub>:H: optical properties



From spectroscopic ellipsometry

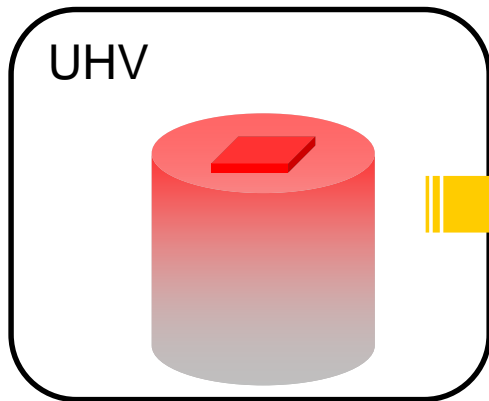
Increasing [CO<sub>2</sub>]/[SiH<sub>4</sub>] ratio leads to a decrease of both:

- **refractive index  $n$**  and
- **extinction coefficient  $k$**
- **Bandgap: + 0.1 eV** for [CO<sub>2</sub>]/[SiH<sub>4</sub>] = 2.5

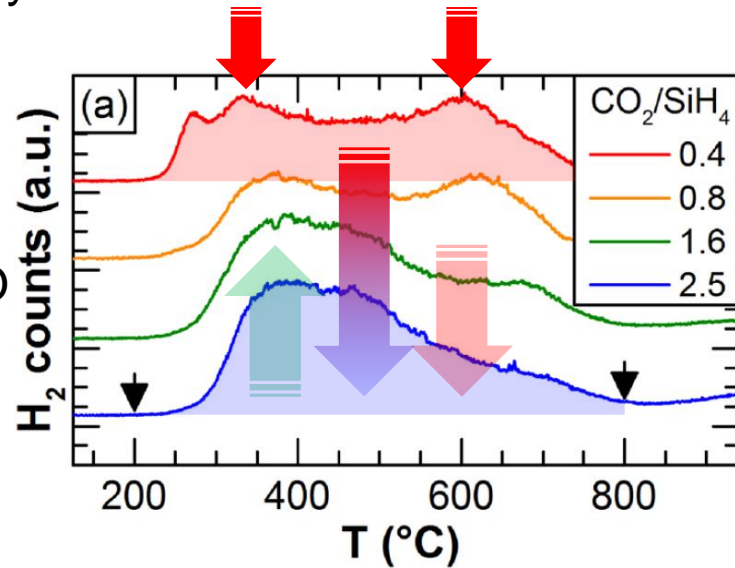
Linked to incorporation of hydrogen\* and oxygen

# a-SiO<sub>x</sub>:H: structural properties

- Thermal desorption spectroscopy to analyse the layer structure



H<sub>2</sub> H<sub>2</sub>O  
O<sub>2</sub>...



## What we observe:

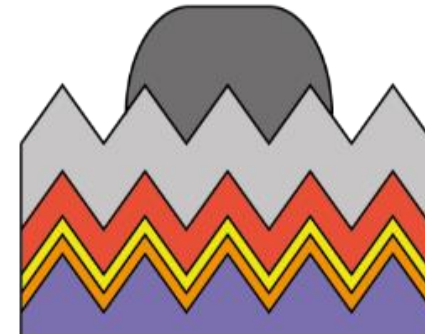
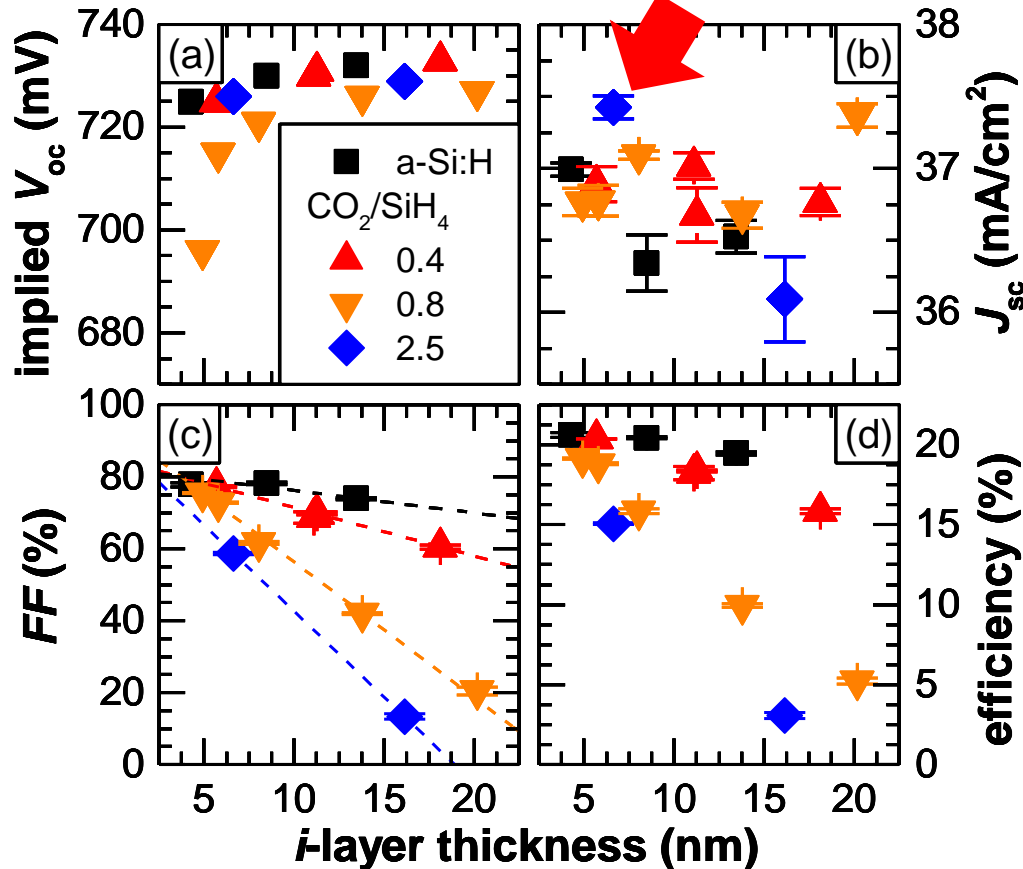
- H<sub>2</sub> effusion spectrum varies high-*T* peak decreases, low-*T* peak increases with CO<sub>2</sub>/SiH<sub>4</sub>
- The area under the curves increases with CO<sub>2</sub>/SiH<sub>4</sub>

## What we learn:

- Structure gets increasingly porous with increasing CO<sub>2</sub>/SiH<sub>4</sub> ratio
- The amount of H<sub>2</sub> in the layer increases with CO<sub>2</sub>/SiH<sub>4</sub>

# a-SiO<sub>x</sub>:H: applied to hole contact

Variation in a-SiO<sub>x</sub>:H thickness with various [CO<sub>2</sub>]/[SiH<sub>4</sub>] ratios



**Good passivation:**  
Implied V<sub>oc</sub>s between  
**720–730 mV**



**Improved current:**  
by up to **0.4 mA/cm<sup>2</sup>**  
(no clear trend with thickness  
due to reduced reflection)\*

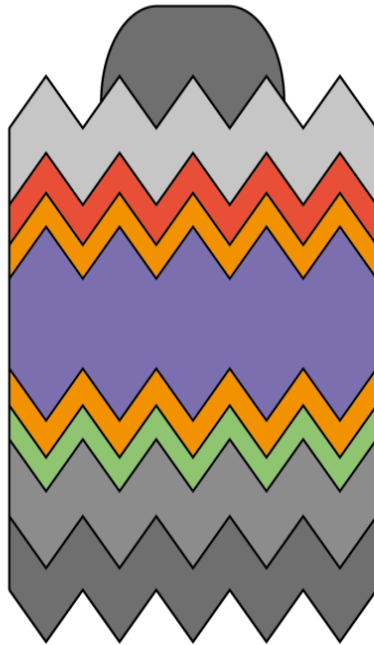


**BUT drop in fill factor:**  
For a-SiO<sub>x</sub>:H cells, strongly  
influenced by [CO<sub>2</sub>]/[SiH<sub>4</sub>]  
ratio and thickness.

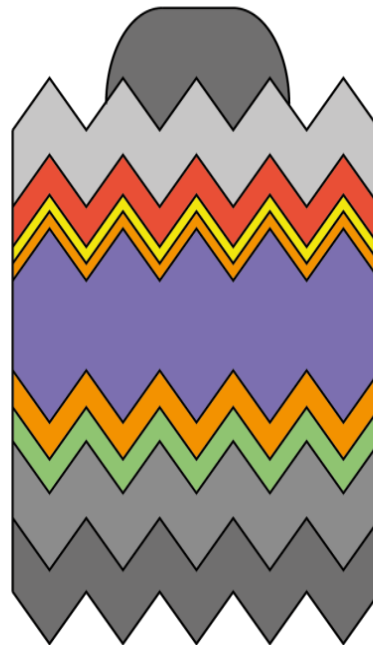


\* Z. C. Holman et al., IEEE JPV, 2(1), 2012

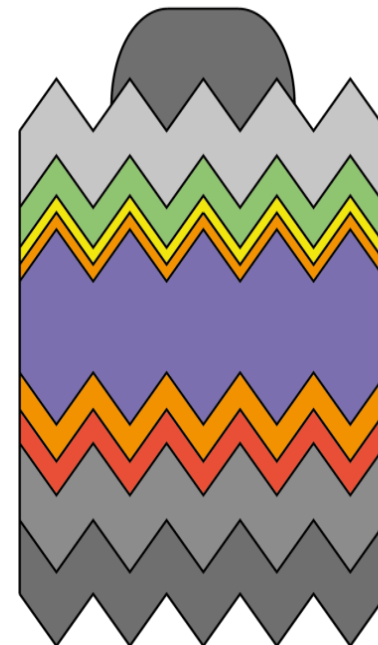
# a-SiO<sub>x</sub>:H permutations



reference

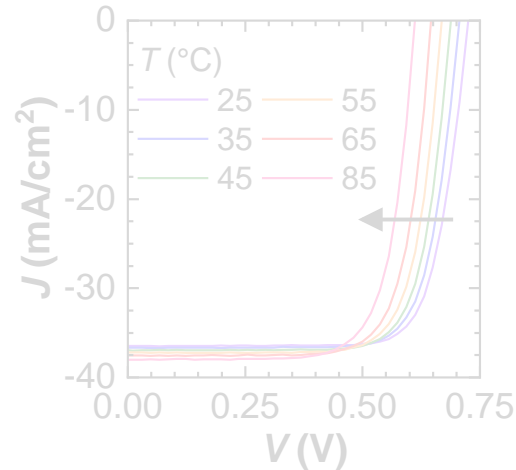
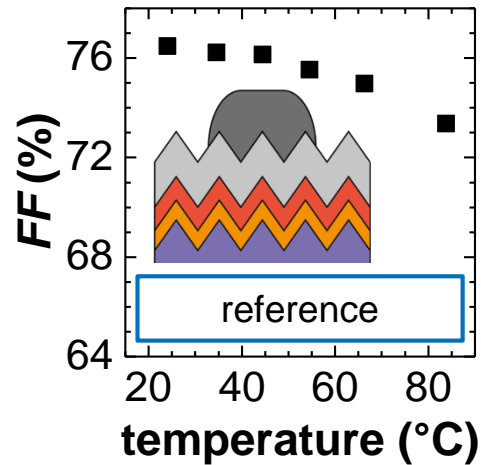


a-SiO<sub>x</sub>:H below *p*

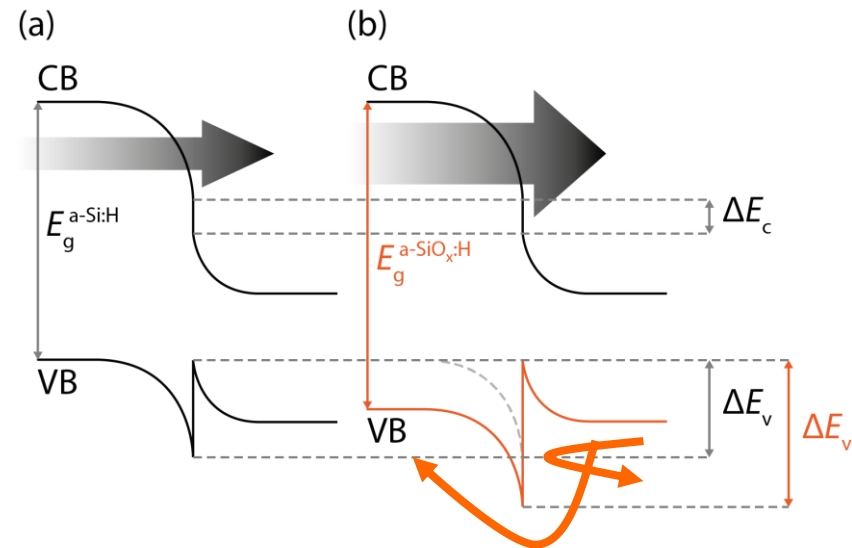
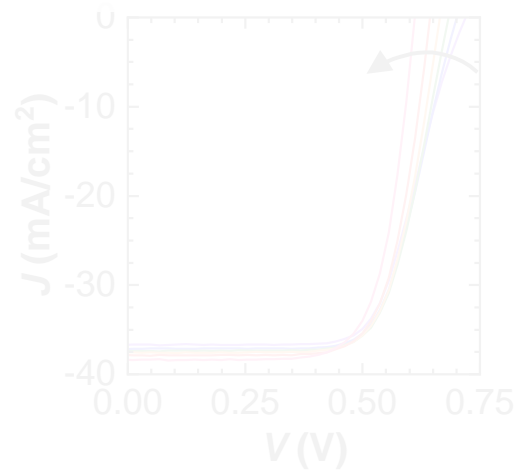
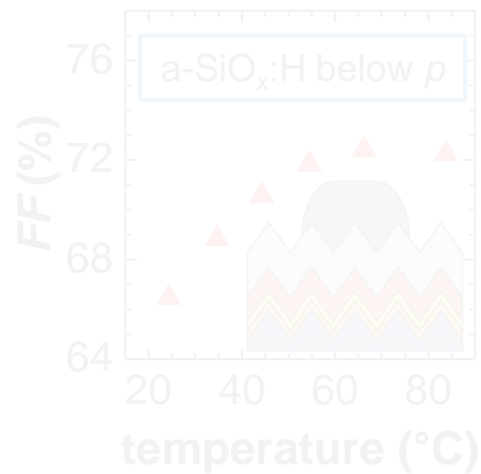


a-SiO<sub>x</sub>:H below *n*

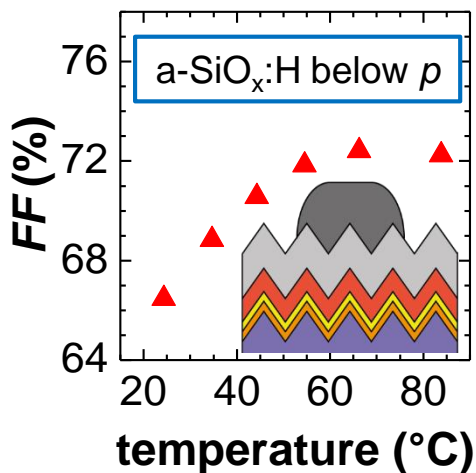
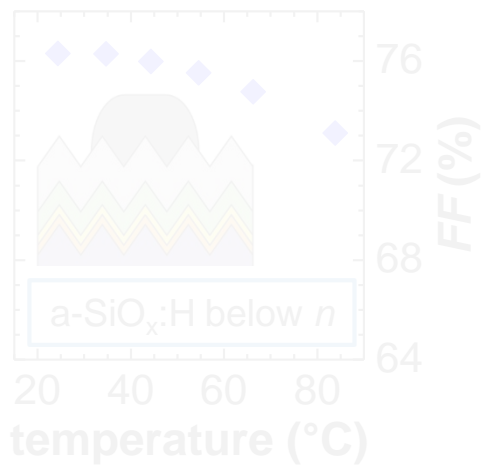
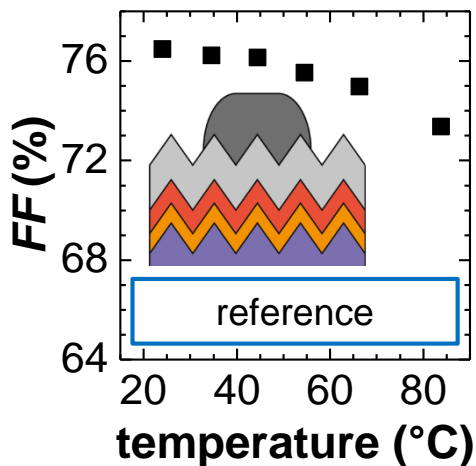
# Wide-bandgap a-SiO<sub>x</sub>:H: *impact on FF*



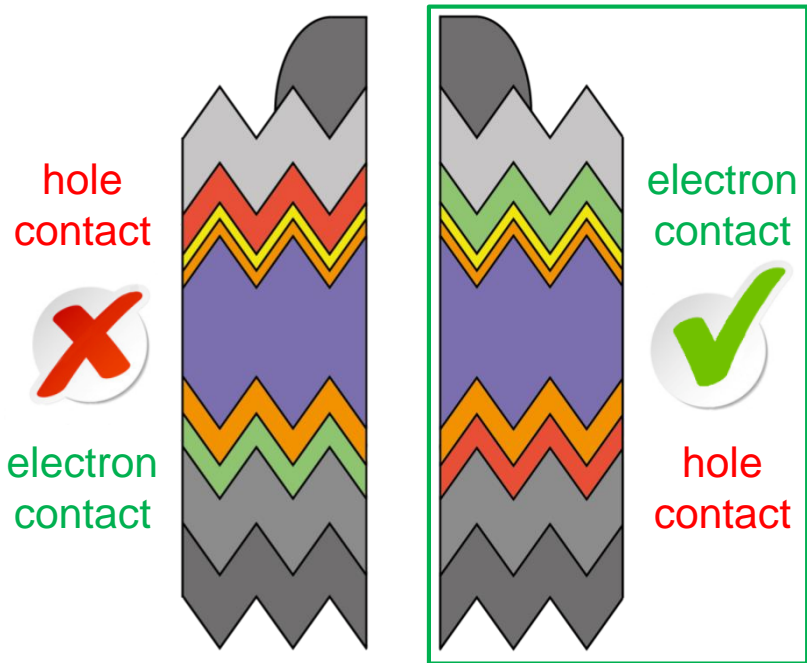
**Due to:**  
 Transport problem  
 associated with **increased**  
**valence band offset**  
 (confirmed by simulation)



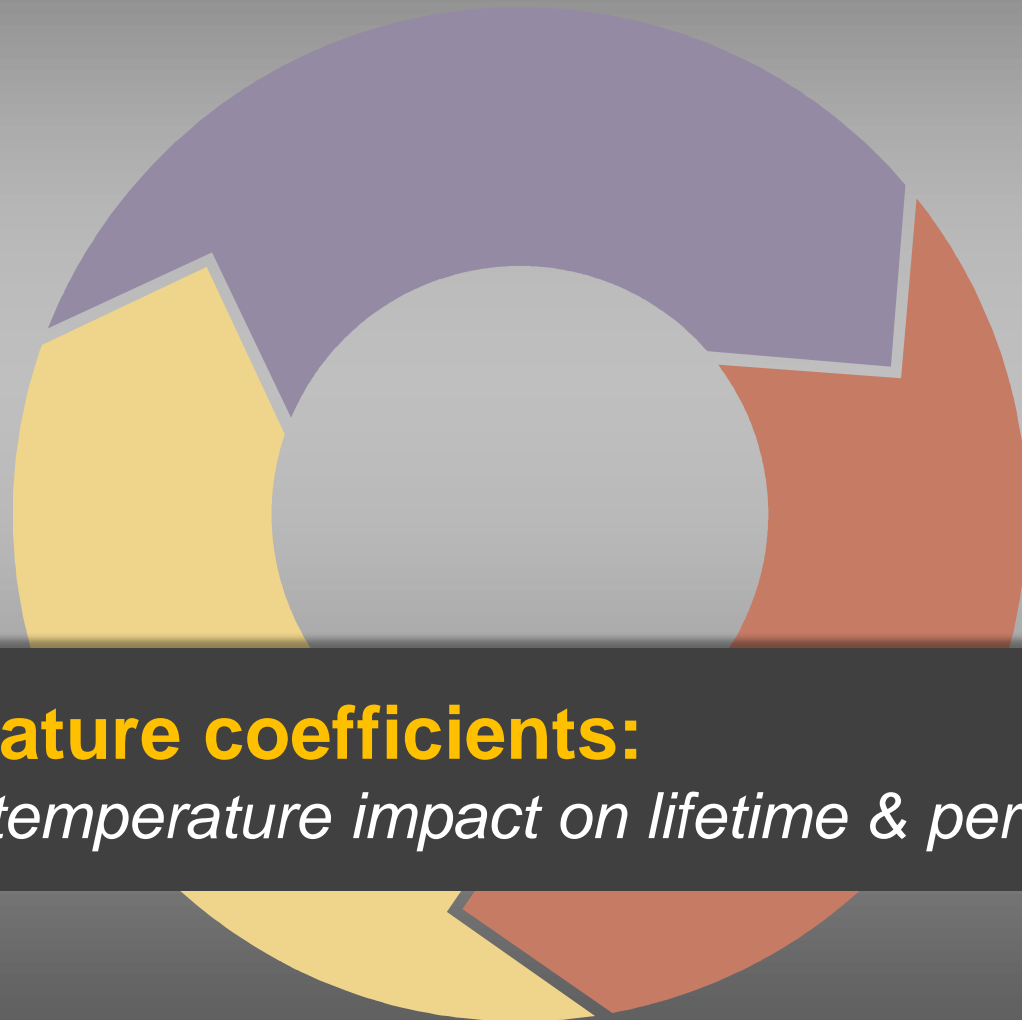
# Wide-bandgap a-SiO<sub>x</sub>:H: *impact on FF*



Confirmation that **holes** are the carriers that are affected most by the a-SiO<sub>x</sub>:H(*i*) layer



Potential gain in cells with hole collection at the rear



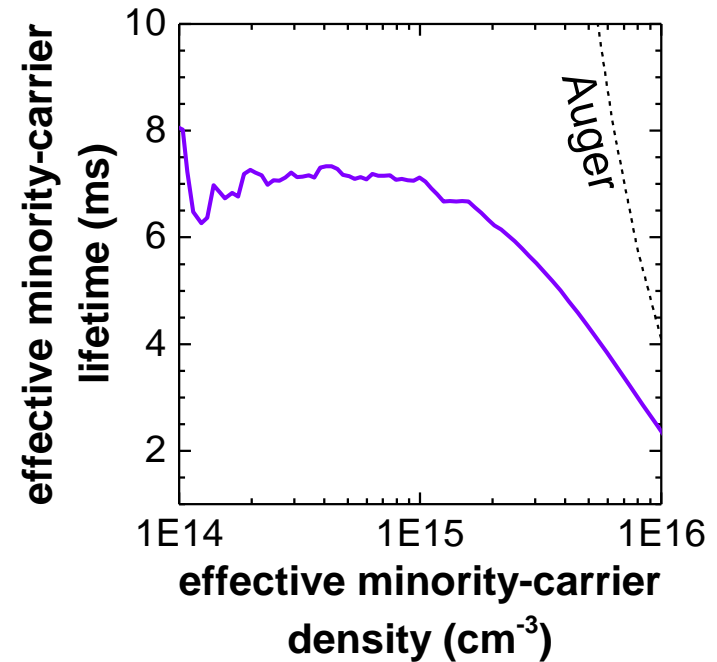
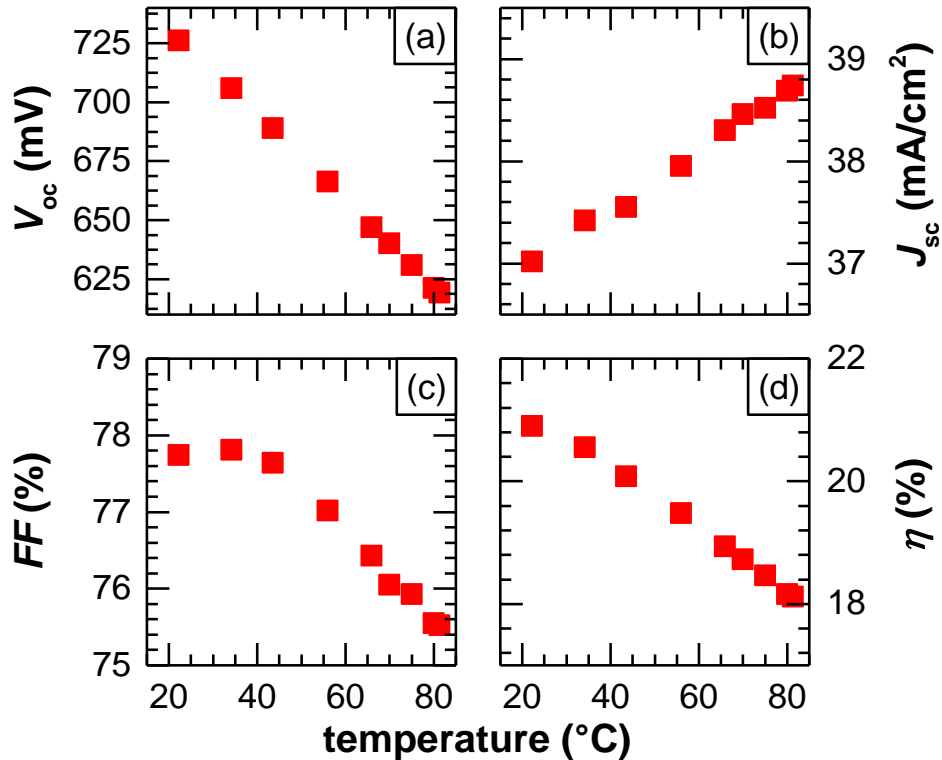
## **Temperature coefficients:**

*Ambient-temperature impact on lifetime & performance*



# Motivation

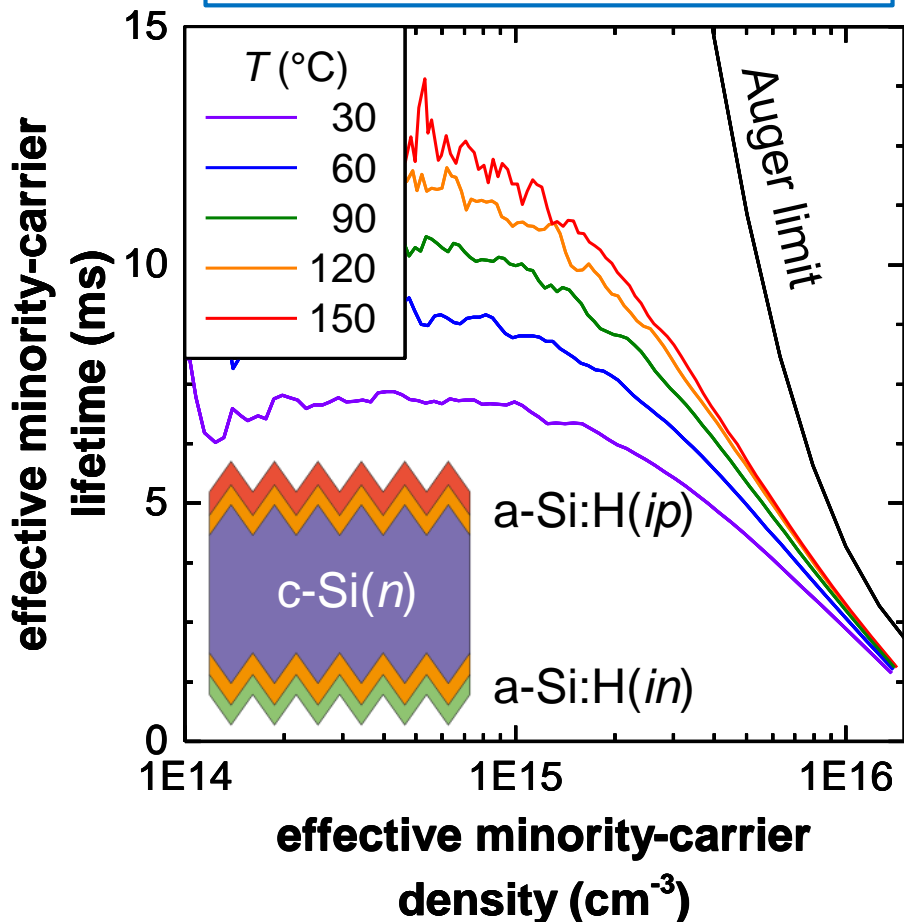
Typical temperature evolution  
of the cell parameters (SHJ solar cell)



Temperature coefficients (TCs) important  
for operation in the field: cell  $T$  up to 90 °C

# Lifetime ( $\tau$ ) measurements: *passivated wafers*

Typical effective lifetime curve:  
Evolution with temperature



Possibly explained by change in **recombination statistics / capture cross-sections** with temperature

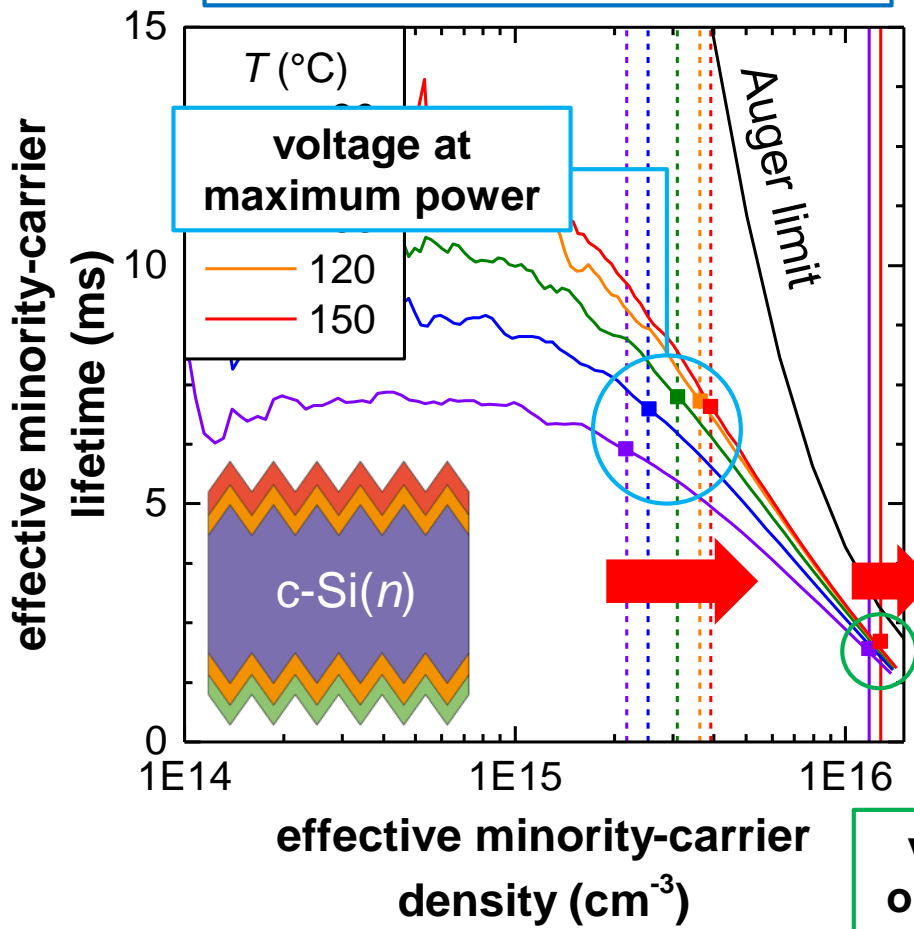
*D. M. Goldie, American J. Material Science, 2013*



cell parameters ( $J_{sc}$ ,  $V_{oc}$ ,  $FF$ )

# Lifetime ( $\tau$ ) measurements: *passivated wafers*

Typical effective lifetime curve:  
Evolution with temperature

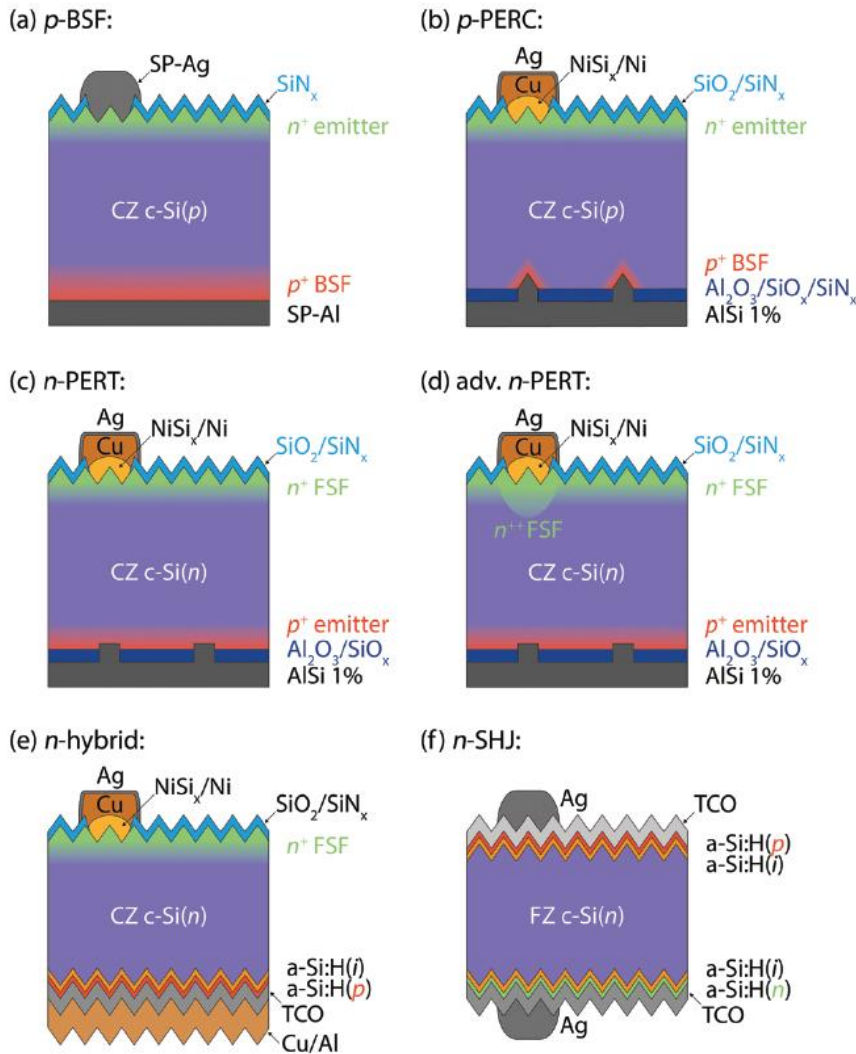



- $iV_{oc}$ 
  - Lifetime Auger-limited
  - weak increase of the lifetime with  $T$
  - BUT** shift to higher injection / voltage
- $iV_{mpp}$ 
  - Lifetime **NOT** Auger-limited yet
  - increasing the lifetime with  $T$
  - AND** shift to higher injection / voltage

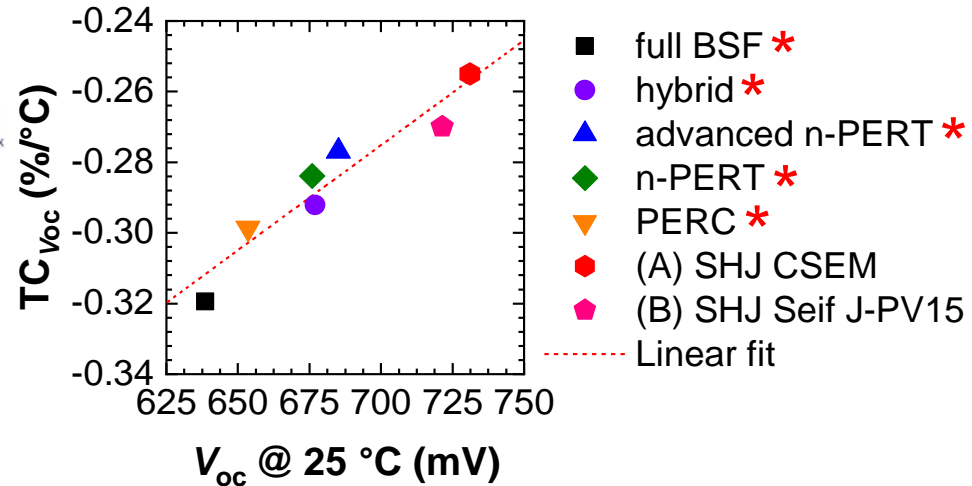
Impact on temperature coefficients of the  $iV_{mpp}$  (i.e.  $iFF$ ) and  $iV_{oc}$ .

voltage at open circuit

# Temperature coefficients (TC): *impact of $V_{oc}$*



\* Samples from: 



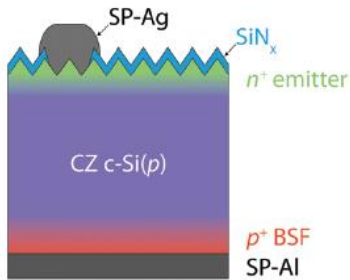
$$\frac{\partial V_{oc}}{\partial T} = - \frac{(V_{g0} - V_{oc} + \gamma kT/q)}{T}$$

M. A. Green, et al., J. Appl. Phys., vol. 58, 1985.

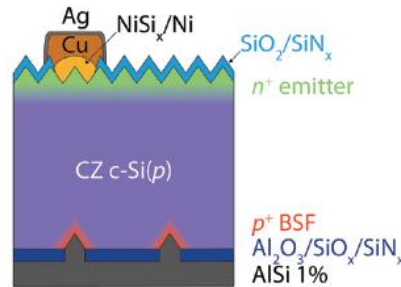
**High-quality passivation (high  $V_{oc}$ )  
crucial for good TCs and  $FF$ !**

# Temperature coefficients (TC): Cells vs. Modules

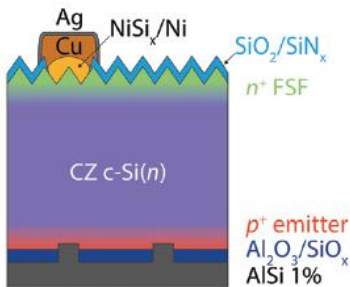
(a) p-BSF:



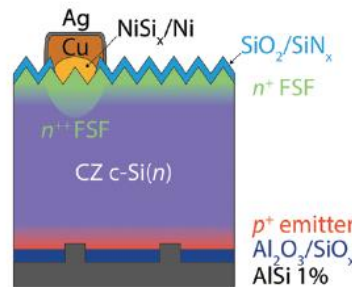
(b) p-PERC:



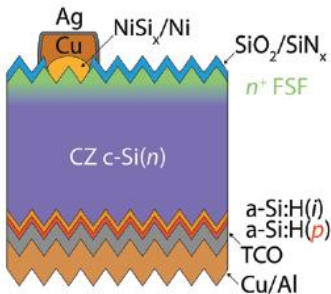
(c) n-PERT:



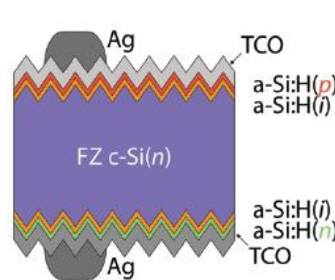
(d) adv. n-PERT:



(e) n-hybrid:



(f) n-SHJ:



Study of temperature coefficients (TC) of **different state-of-the-art cells** and **comparison to modules**

- $TC_{V_{oc}}$  and  $TC_{J_{sc}}$  are similar BUT  $TC_{V_{mpp}}$  is worse for modules



Additional series resistance induced by the interconnections between the cells in a module.

**High  $V_{oc}$  and low-resistive interconnections** are essential for hot and sunny climates.



## **Alternative transparent electrodes:**

*Atomic-layer-deposited ZnO:Al & Organic overlayers*

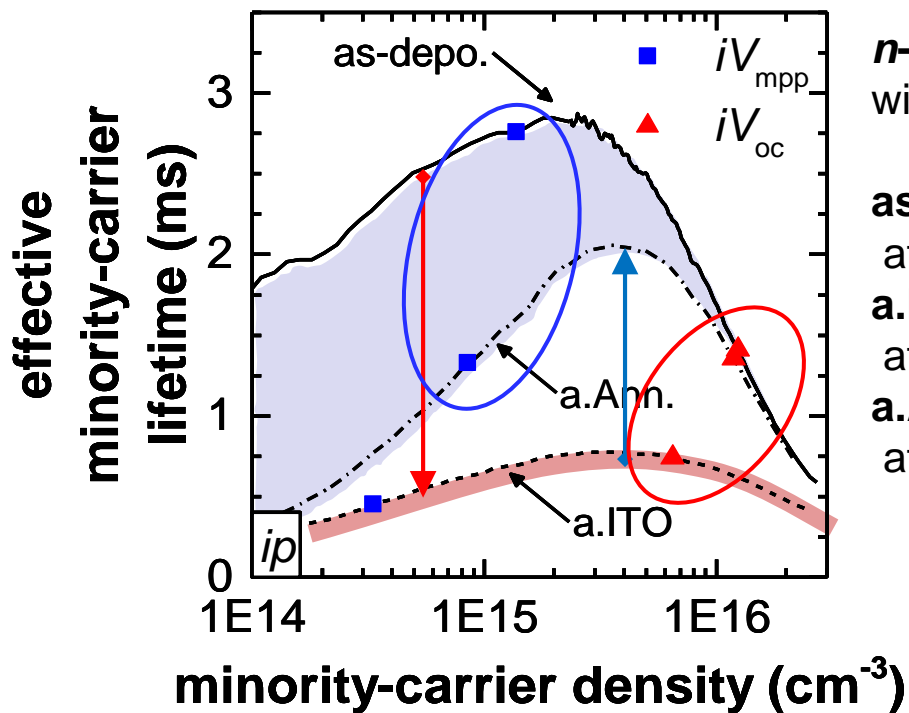
# Motivation

Thinner a-Si:H layers at the front

(Permanent) damage associated with sputtering possible

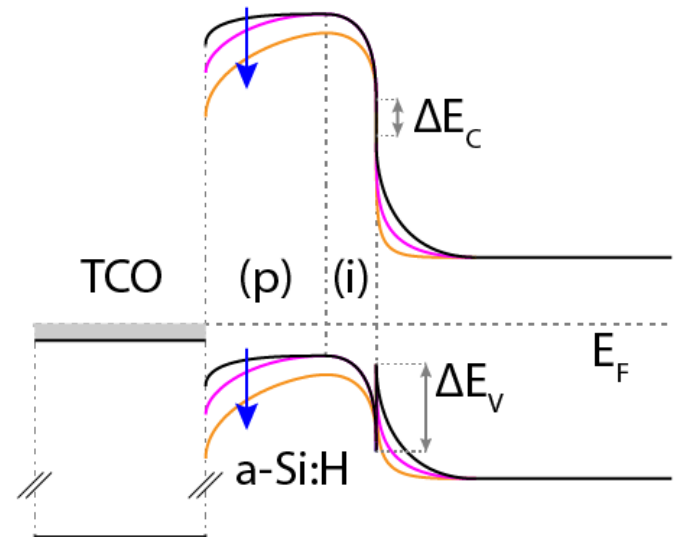
Higher current output (increased  $J_{sc}$ )

Degradation at lower injection: non-optimal TCO work function / field effect



n-type wafer with  $ip/ip$

as-depo.: after PECVD  
 a.ITO: after sputtering  
 a.Ann.: after annealing



**Solution:** Soft deposition technique or protective layer

**Solution:** TCO with an optimized work function

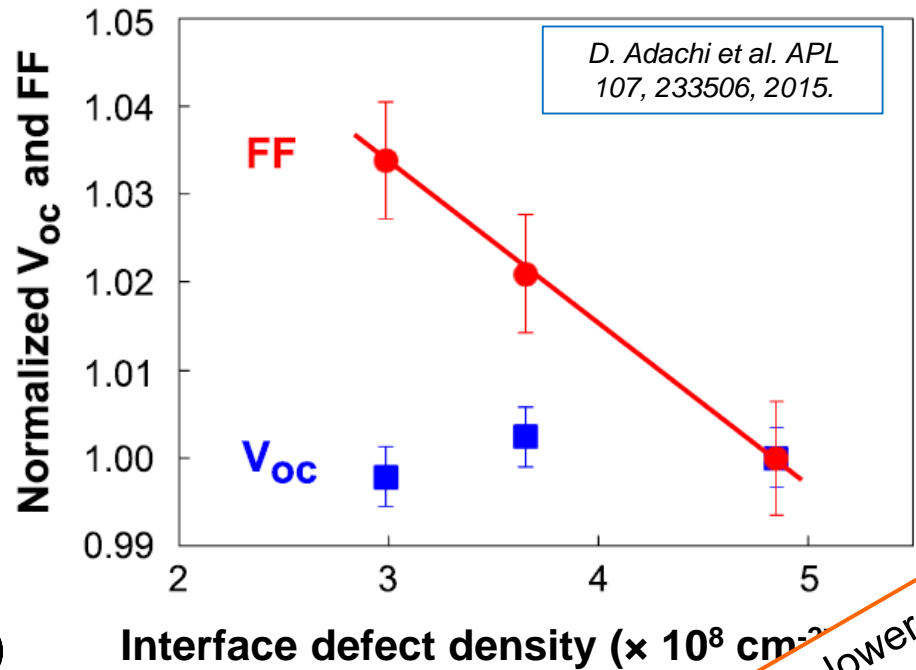
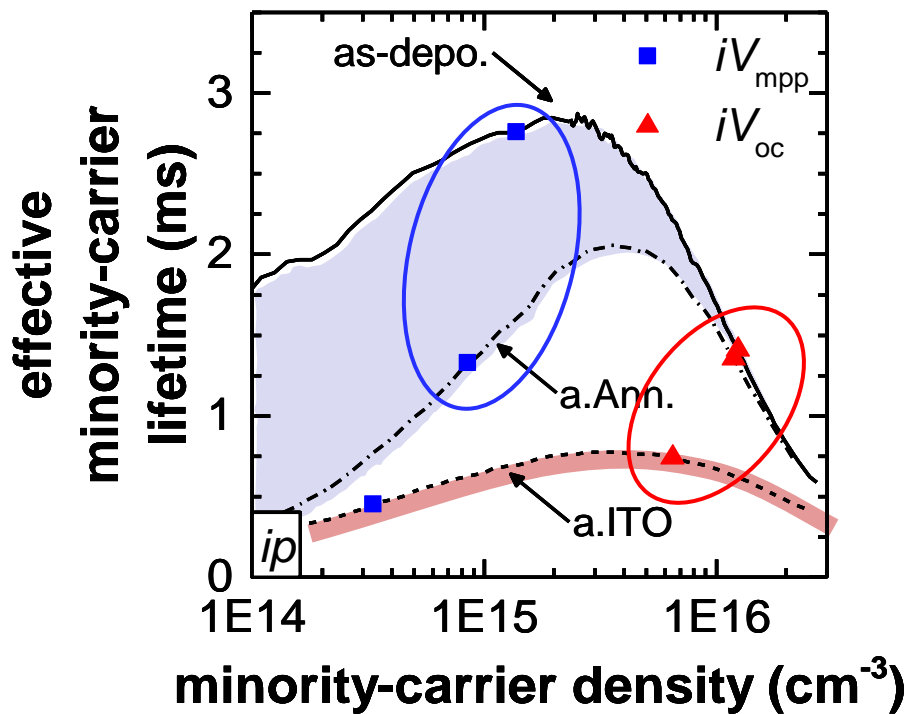
# Motivation

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(Permanent) damage associated with sputtering possible

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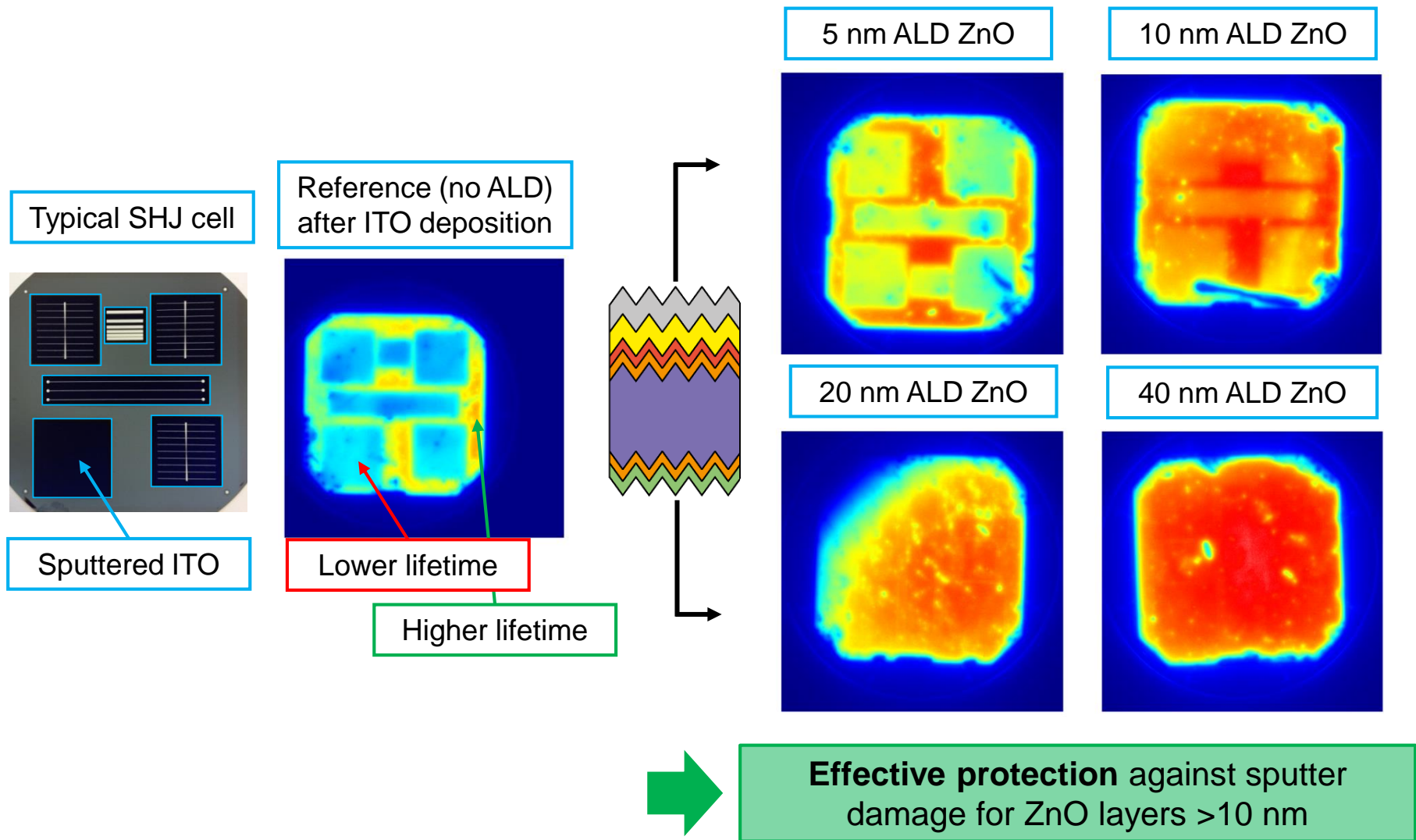
**Solution:** Soft deposition technique or protective layer

**Solution:** TCO with an optimized work function

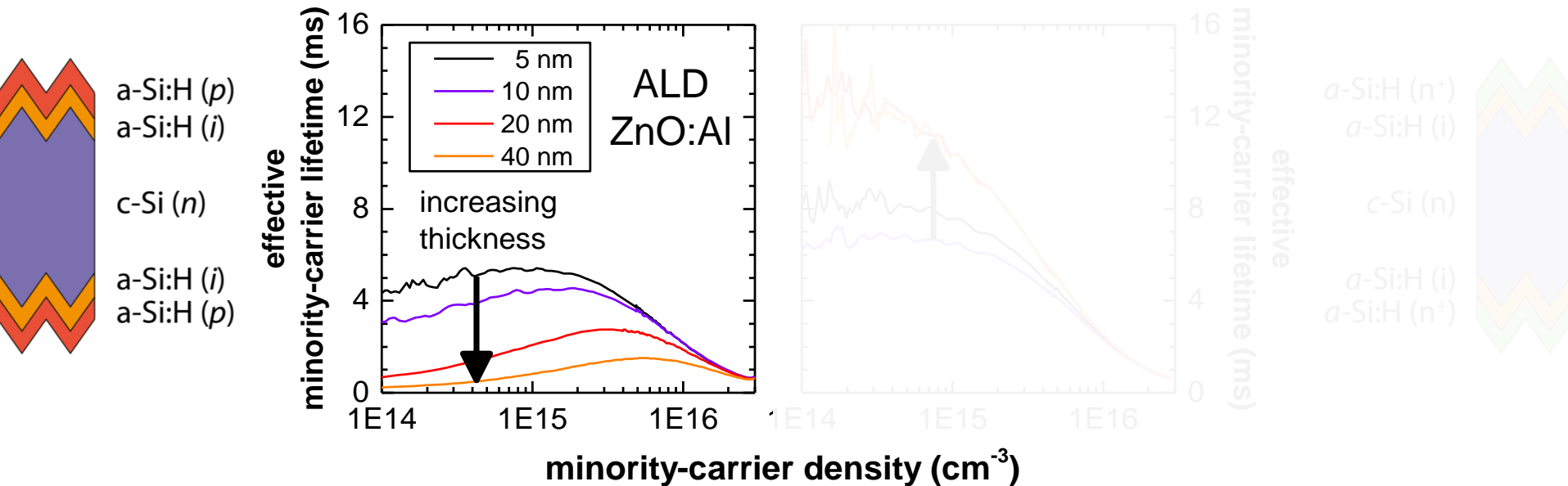
+ lower defect density!



# ALD ZnO:Al layer vs. sputter-damage



# Lifetime variation: a workfunction effect



**Negative effect** → lower *iFF*




**Positive effect** → higher *iFF*

**Solutions:** optimizing ZnO, applying different TCO or organic semiconductors.

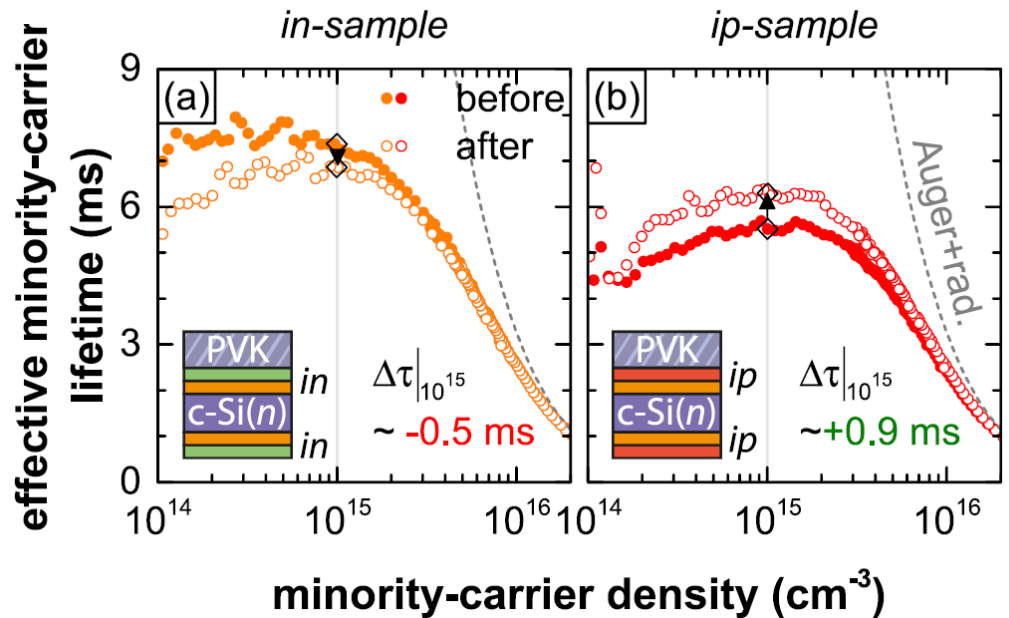
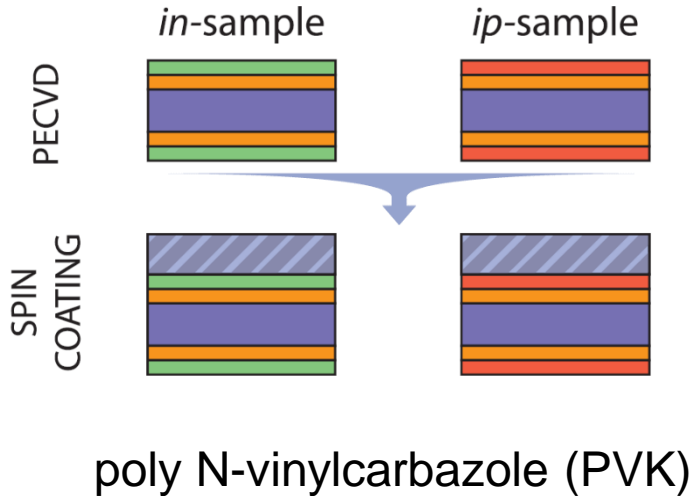
**Potential application on the electron-collecting side of the device**

**Work function engineering** crucial for high *FF* values.

# Alternative materials: Organic overlayers

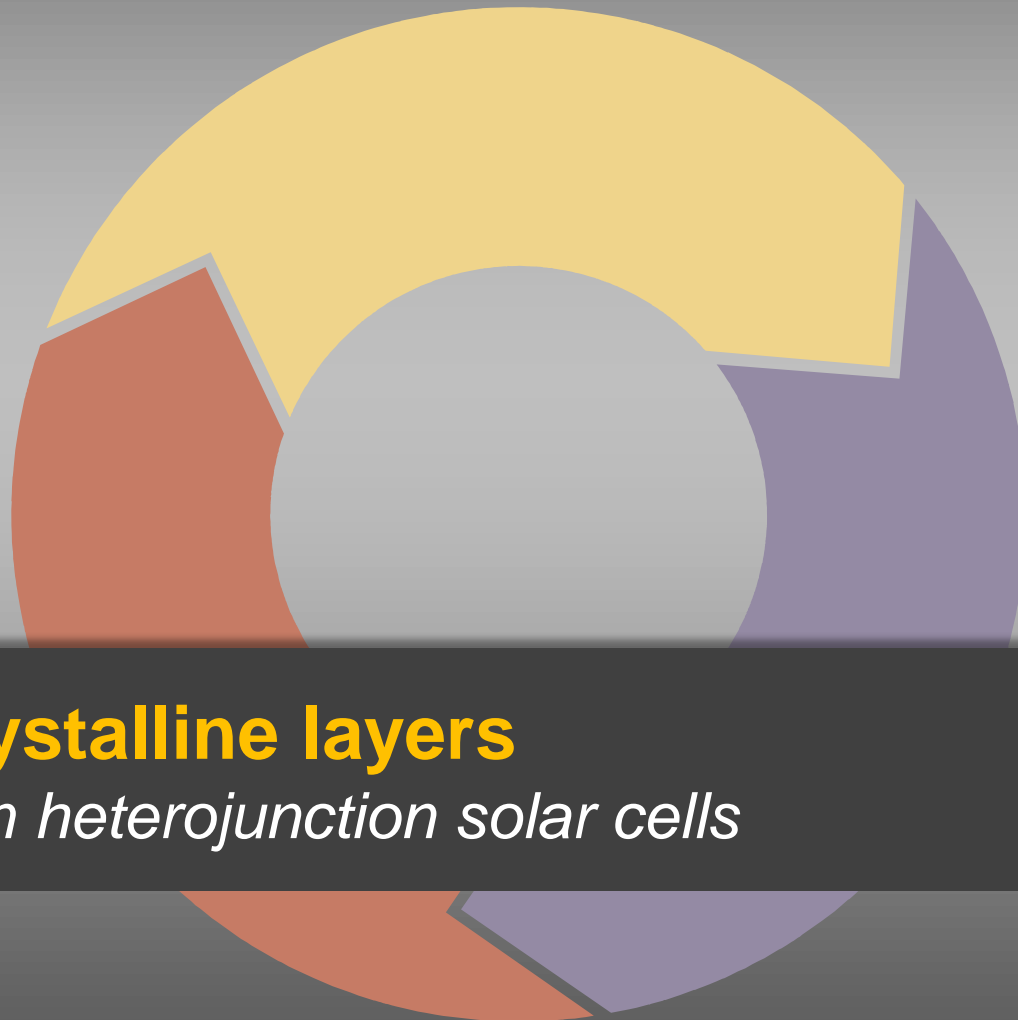
$a\text{-Si:H}(p)$    $a\text{-Si:H}(n)$    $a\text{-Si:H}(i)$  

$c\text{-Si}(n)$   PVK 



Inverse effect on *in/in* (**NEGATIVE**) and *ip/ip* (**POSITIVE**) passivated samples.

Work function engineering:  
Tunable effect with variation of the PVK doping.



## **Nanocrystalline layers**

*For silicon heterojunction solar cells*

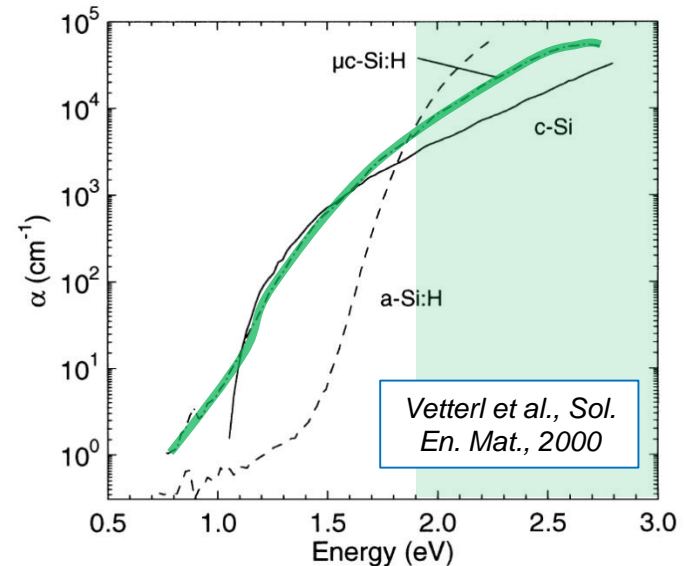
# Motivation

## Benefits of nanocrystalline materials

- **Optically:** *indirect bandgap of c-Si*
  - better response at short wavelengths
- **Electrically:** *higher doping efficiency and improved transport properties*
  - suppression of Schottky barriers  
→ improved contact resistivity

## Requirements for PECVD nc-Si layers

1. **Fast nucleation** (thicknesses ~10–20 nm)
2. **Sufficiently high crystallinity**
3. **‘Soft’ deposition for pristine passivation**



# Strategies for nanocrystalline layers

method	layer crystallinity/ nucleation speed	application in devices	
CO <sub>2</sub> plasma treatments	✓	✗	
a-SiO <sub>x</sub> :H buffer layers	✓ ✓	✗ ✗	
<div style="display: flex; align-items: center;"> <div style="border: 1px solid red; padding: 5px; transform: rotate(-15deg); color: red; font-weight: bold; margin-right: 10px;">Non-standard</div> <div style="font-size: 2em; margin-right: 10px;">✗</div> <div style="font-size: 3em; margin-right: 10px;">{</div> <div> <p>SiF<sub>4</sub> nucleation layers</p> <p>SiH<sub>4</sub> → Si<sub>2</sub>H<sub>6</sub></p> <p>H<sub>2</sub> → D<sub>2</sub></p> </div> </div>	✓ ✓	✓	
	SiH <sub>4</sub> → Si <sub>2</sub> H <sub>6</sub>	✓	✓
	H <sub>2</sub> → D <sub>2</sub>	✓	✓
Temperature	✓ ✓	✓	
✗ Higher deposition frequency (VHF)	✓ ✓ ✓	✓	
<div style="display: flex; justify-content: space-between;"> <div style="font-size: 2em; color: green; margin-right: 10px;">➡</div> <div>Low frequency and higher pressure</div> <div style="font-size: 2em; color: green; margin-left: 10px;">➡</div> </div>	✓ ✓	✓ ✓	

# nc-Si:H(*n* or *p*): device results

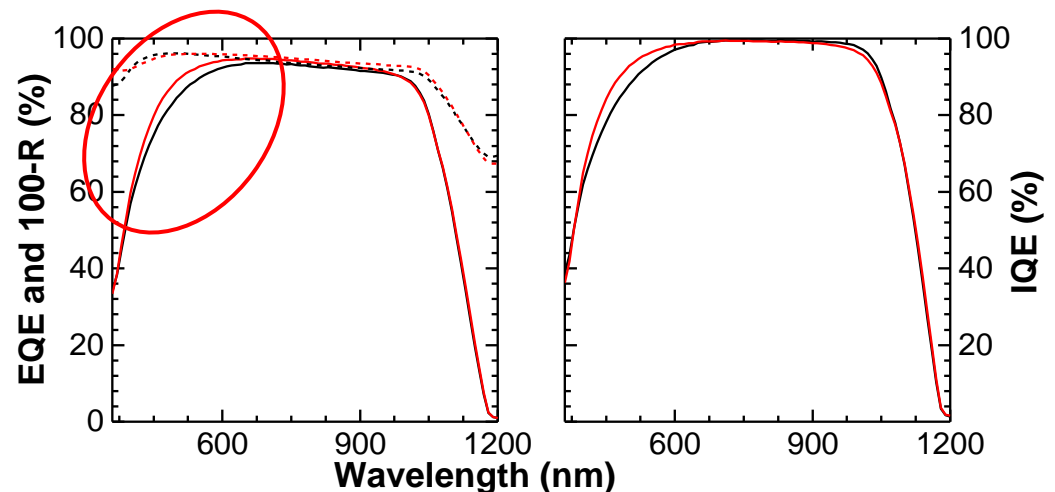
nc-Si:H(*n*) or nc-Si:H(*p*) layers implemented into SHJ devices

[reference values]

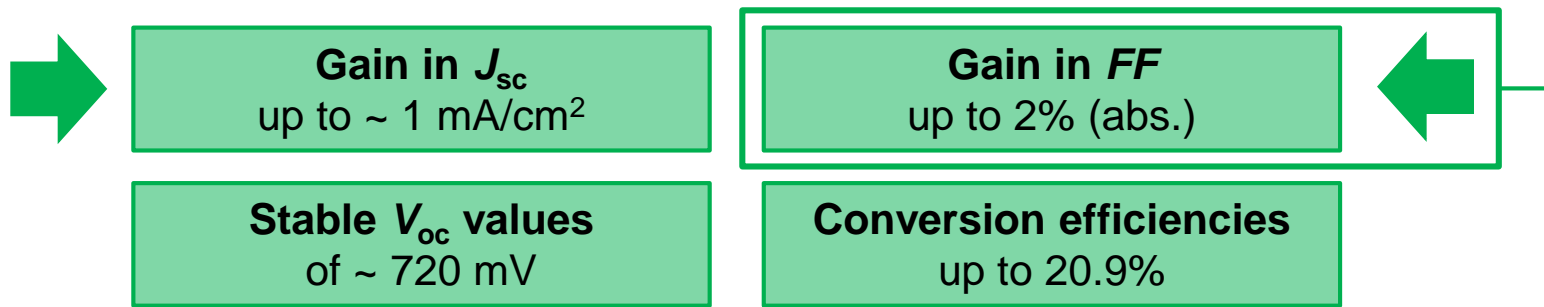
Deposition regime	nc-Si:H(X)	position	$V_{oc}$ (mV)	$J_{sc}$ (mA/cm <sup>2</sup> )	$FF$ (%)	$\eta$ (%)
81.36 MHz (2 mbar)	<i>p</i>	front	717 [719]	37.7 [36.8]	72.6 [72.7]	19.6 [19.2]
13.56 MHz (SiF <sub>4</sub> ), 40.68 MHz (> 2 mbar)	<i>i</i> <sub>SiF<sub>4</sub></sub> (nucl.) <i>p</i>	front	718 [718]	36.0 [37.1]	78.4 [76.7]	20.3 [20.4]
13.56 MHz (> 2 mbar)	<i>p</i> <i>n</i>	rear front	720 719	36.5 37.0	79.2 78.7	20.8 20.9

## All cells

Textured, 1-5 Ωcm, nominal 240 μm, *n*-type FZ, 2 × 2 cm<sup>2</sup>, with screen-printed Ag front contacts and full Ag contact at the rear.



# nc-Si:H(*n* or *p*): device results

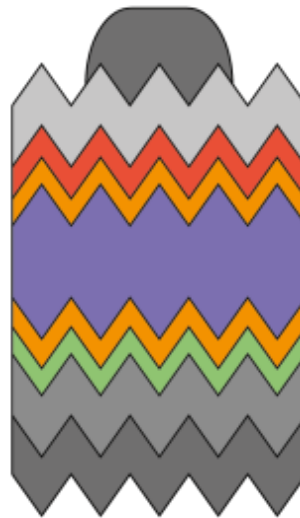


## Requirements

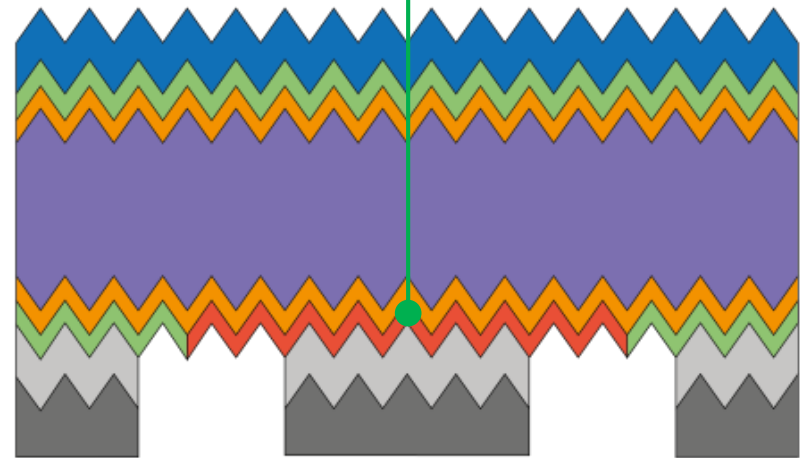
1. Fast nucleation ✓
2. High crystallinity ✓
3. 'Soft' deposition ✓

Achieved with **simple, industry-compatible process** using standard gases.

**Readily applicable** without additional costs.



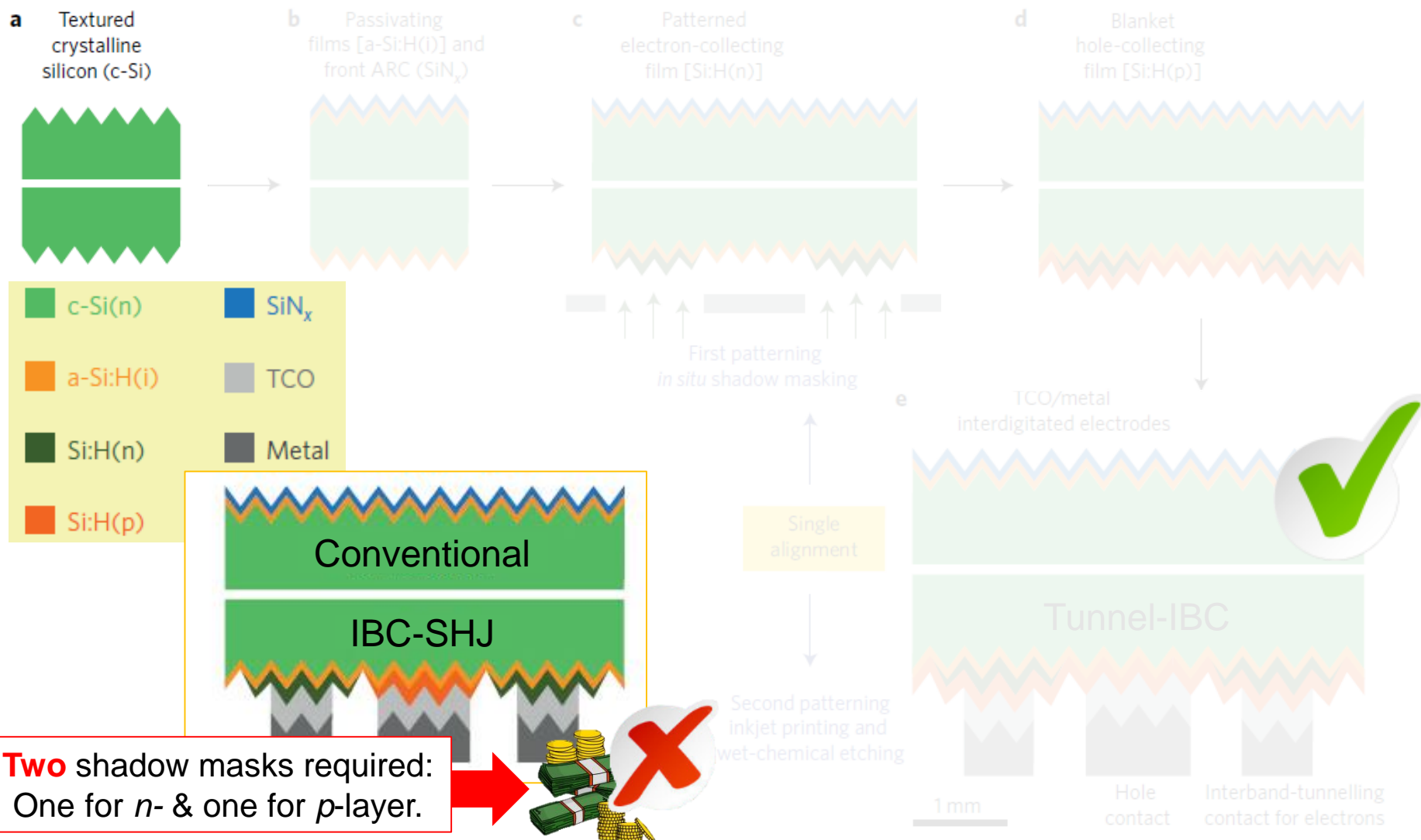
**Standard 2-side-contacted SHJ (full area)**



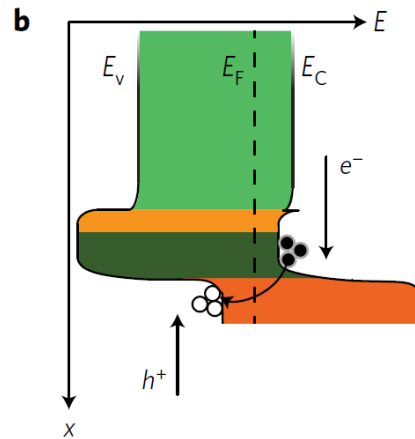
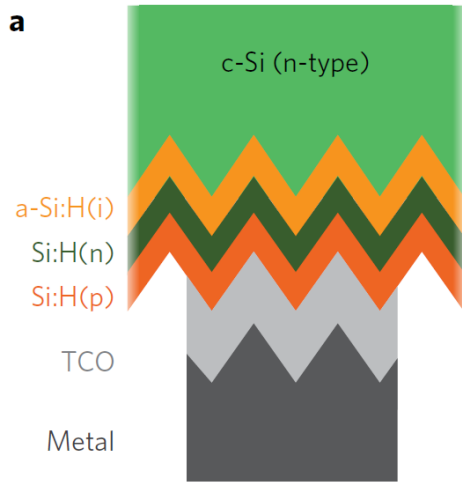
**Rear-contacted SHJ (reduced contacting area)**



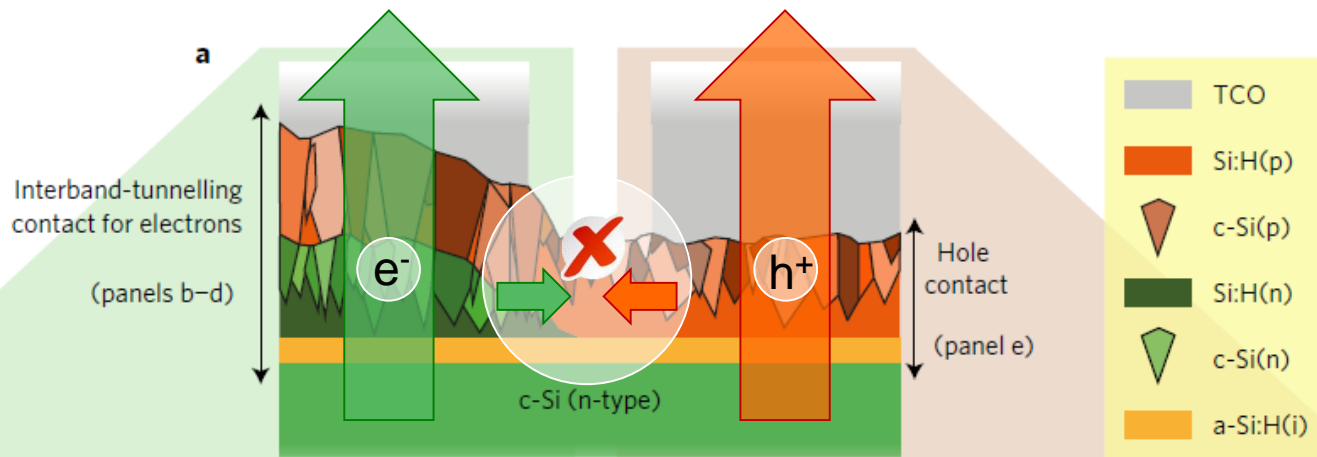
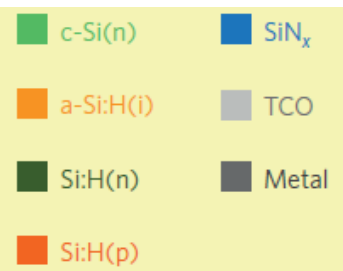
# Rear-contacted cells: *nc-Si:H*(*n* and *p*) inside



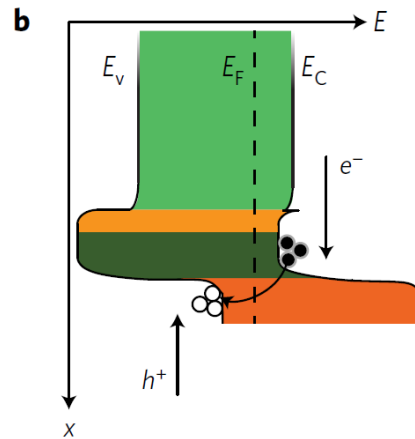
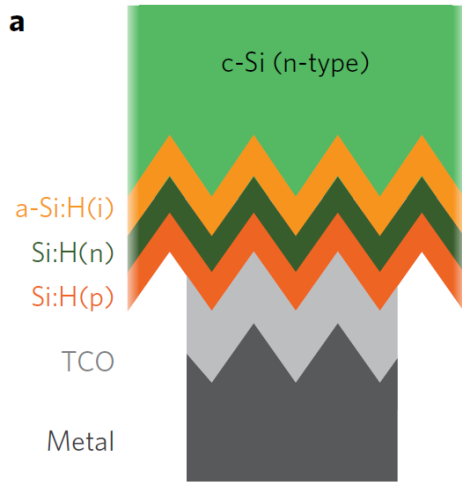
# Rear-contacted cells: *nc-Si:H(n and p) inside*



- Efficient interband-tunneling contact for electrons.
- Minimized resistive losses (nc-Si) and optimal carrier selectivity ( $e^-$ )
- Low lateral conductance to prevent shunts, thanks to **grain boundaries** and **incubation layer**



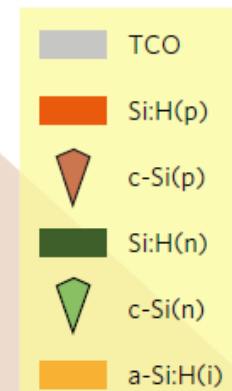
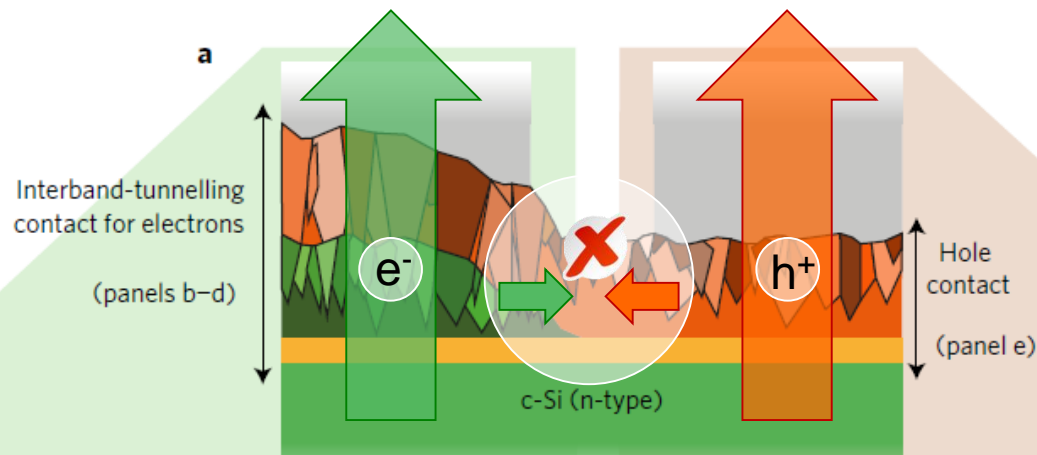
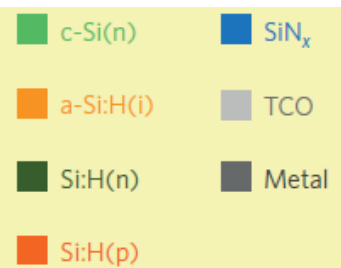
# Rear-contacted cells: *nc-Si:H(n and p) inside*



**Fraunhofer**  
ISE

CalLab  
PV Cells

**Certified efficiency**  
Area = 9.00 cm<sup>2</sup> (da)  
 $J_{sc} = 40.65 \text{ mA}\cdot\text{cm}^{-2}$   
 $V_{oc} = 728.49 \text{ mV}$   
 $FF = 76.36\%$   
 **$\eta = 22.61\%$**



# Conclusions

## Ambient-temperature impact

- increasing lifetime with temperature
- $TC_{V_{oc}}$  depends on  $V_{oc}$ , device structure and materials
- Modules need high  $V_{oc}$ s and low-resistive cell interconnections

## Wide-bandgap oxides

Electrons may, but **holes should not** be collected through the window-layer

→ rear hole collection

→ gain in  $J_{sc}$  w/o losses in  $FF$   
+ 0.4 mA/cm<sup>2</sup> shown

**Nanocrystalline layers** can help improve both optical and electrical device performance

→ gain in  $J_{sc}$  and  $FF$   
+1 mA/cm<sup>2</sup> and +2% shown

## Alternative transparent electrodes

*Atomic-layer-deposited ZnO:Al*

- for effective sputter-damage protection and promising electron-collecting layer

→ potential gain in  $J_{sc}$  and  $FF$

## Alternative transparent electrodes

*Organic overlayers*

- work function engineering for improved contacts

→ potential gain in  $FF$



**UNSW**  
SYDNEY

Australia's  
Global  
University

The logo for UNSW Sydney is displayed on a yellow background. It features the university's crest, which includes a shield with a red cross and a kangaroo, topped with a banner that reads "MANU ET MENTE".



**Passivating contacts**  
with Transition Metal Oxides  
(TMO) deposited by **PECVD**

## Why TMOs?

- Relatively wide band gaps, yet small conduction and valence band offsets
- Promising materials for electron- (e.g.  $\text{TiO}_x$ ) and hole-collection (e.g.  $\text{WO}_x$ )
- Fixed charges for passivation

## State-of-the-art deposition for TMOs

- Atomic Layer Deposition
- Sputtering

**Our approach**  
**PECVD**

## Why PECVD?

- Common in industry
- High throughput
- Wider parameter space (temperature, pressure, gas ratios,...)
- Possibility to use other precursor gases (vary growth mode and material properties)

## Challenges?

- Uniformity of thin layers
- Thermal stability
- Additional passivation layer needed?

**Partners:**



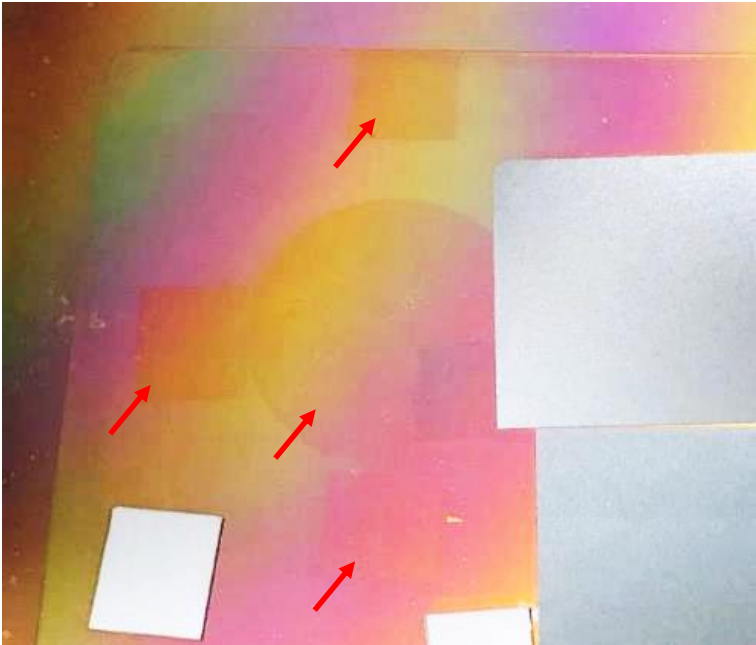
**MEYER BURGER**

**SUNRISE GLOBAL SOLAR ENERGY**

Johannes P. Seif, Anh Le, and Ziv Hameiri

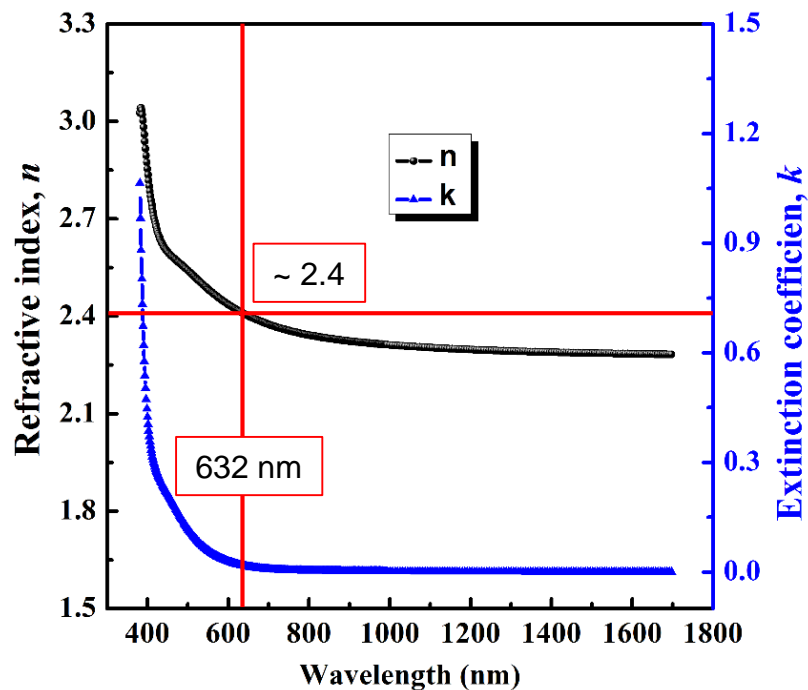


**Modifications of the AK-800**  
Delivery of new precursors  
and first  $\text{TiO}_x$  depositions

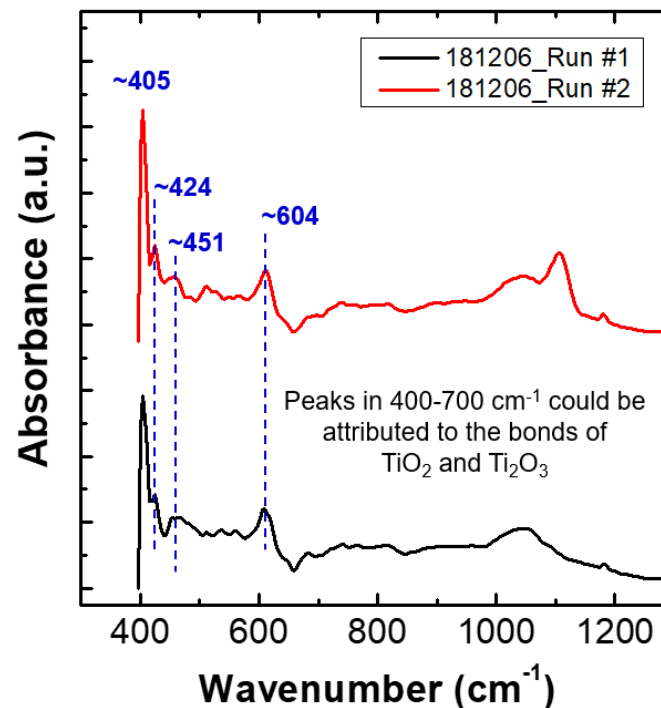


# TMO depositions: *First results*

Spectroscopic Ellipsometry



Fourier-Transform Infrared Spectroscopy (FTIR)



**Thickness:** 7.2 nm  
**Refractive index:** 2.4 @ 632 nm





**Other ongoing projects:**  
With national (incl. UNSW) and international partners

- **Metal work function impact on recombination** (ANU and KAUST)
- **Temperature dependence on cell performance** (KAUST)
- **Hydrogen migration in c-Si wafers** (UNSW, Phill Hamer)
- **Defect parameters of passivated interfaces** (UNSW, Michelle Vaqueiro Contreras)
- **Cell perimeter recombination** (UNSW)



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**University of Twente**  
*The Netherlands*



**UNSW**  
SYDNEY

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# Thank you for your attention!